

Superlattice structures with Distributed Bragg Reflector for intense spin polarized electron beams

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PI Meeting, Nov 17 2025

Outline

- III-V photocathode for high QE and ESP
 - Lifetime, QE, and ESP tradeoffs
- Design of the SL-DBR
- Experimental Results on QE and ESP
- Future Developments
- Conclusions

Objectives and Budget

Milestone 1: *Demonstrate SL-DBR GaAsP/GaAs photocathode capable to achieve $QE > 10\%$ and $ESP > 80\%$ at ~ 780 nm.*

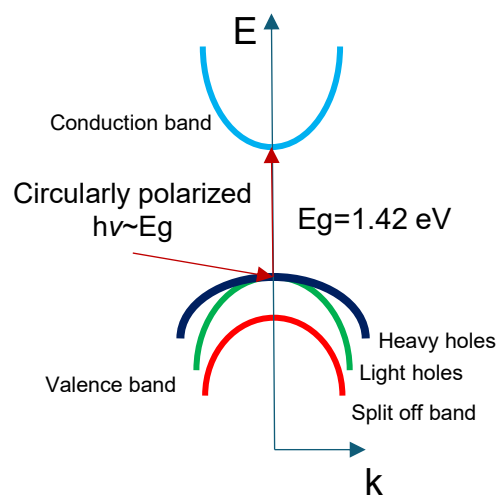
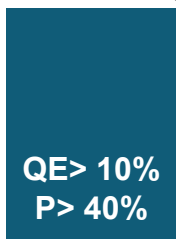
Milestone 2: *Demonstrate SL-DBR GaAsP/InGaAs photocathode lattice matched on GaAs capable to achieve $QE > 10\%$ and $ESP > 90\%$ at ~ 800 nm.*

Milestone 2: *Demonstrate SL-DBR GaAsP/GaAsSb photocathode lattice matched on GaAs capable to achieve $QE > 10\%$ and $ESP > 90\%$ at ~ 1030 nm.*

WBS or ID #	Item/Activity	Baseline Total Cost (FY24)	Baseline Total Cost (FY25)	Costed & Committed (AY\$)	Estimate To Complete (AY\$)	Estimated Total Cost (AY\$)
1	Photocathode design	\$50,000.00	\$50,000.00	\$80,000.00	\$20,000.00	\$100,000.00
2	Photocathode growth	\$50,000.00	\$150,000.00	\$50,000.00	\$150,000.00	\$200,000.00
3	Photocathode characterization	\$27,000.00	\$173,000.00	\$122,212.82	\$77,787.18	\$200,000.00
Totals:		\$127,000.00	\$373,000.00	\$252,212.82	\$247,787.18	\$500,000.00

GaAs based photocathodes

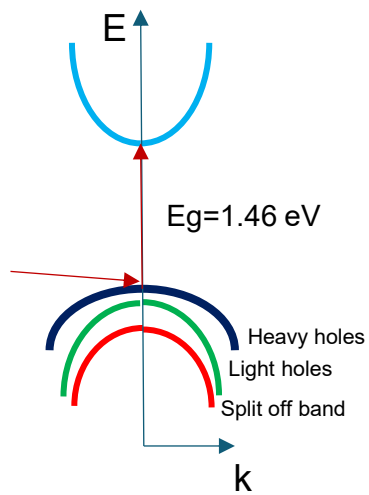
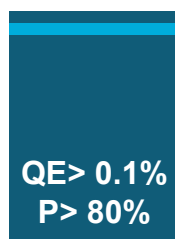
Bulk GaAs
(no layer - 1 material)



**Polarization limited by
energy degeneracy**

D.T. Pierce *et al.*, *Phys. Lett.* **51A**, 465 (1975)

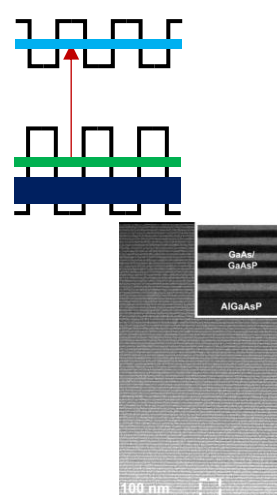
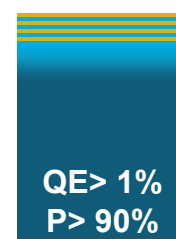
Strained GaAs
(2 layer – 2 materials)



**QE and P limited by
optical absorption and
crystal defects**

T. Maruyama *et al.*, *Phys. Rev. B*, **46**, 4261 (1992)

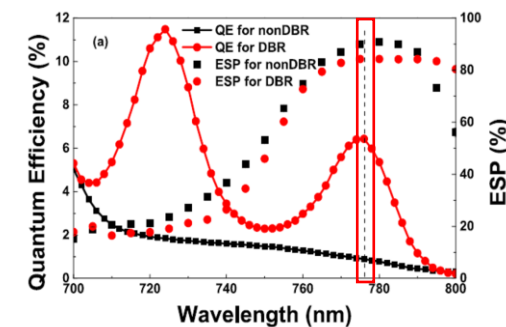
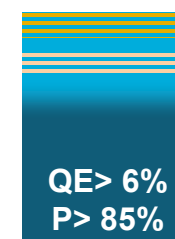
III-V GaAs SuperLattices
(~30 layers – 3 materials)



**QE limited by optical
absorption and crystal
defects**

X. Jin *et al.*, *Appl. Phys. Lett.* **105**, 203509 (2014)

III-V GaAs SL with DBR
(~60 layers – 5 materials)

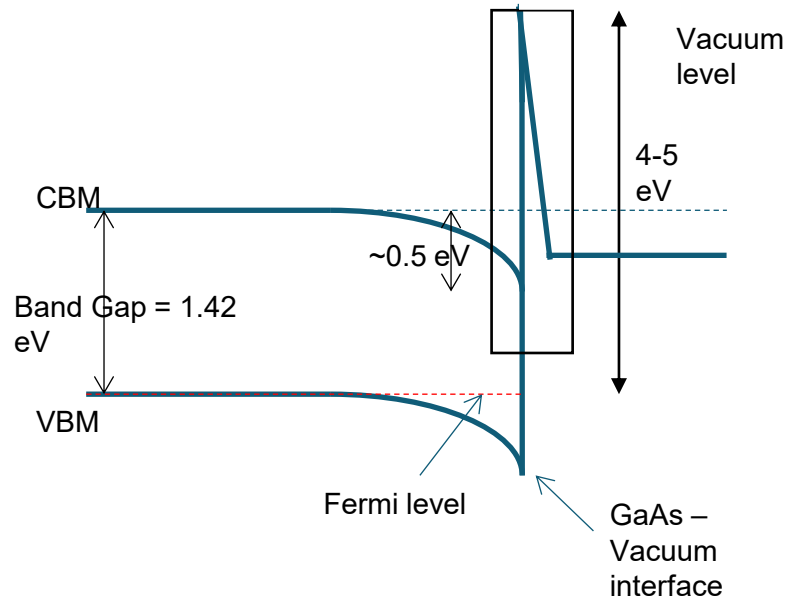


Inspirational work

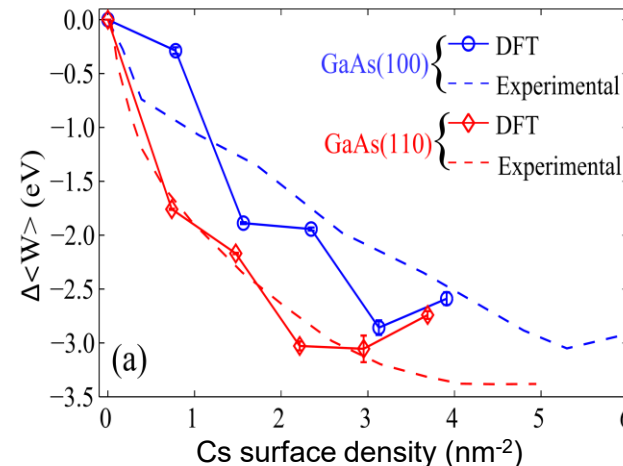
W. Liu *et al.*, *Appl. Phys. Lett.* **109**, 252104 (2016)

Negative Electron Affinity

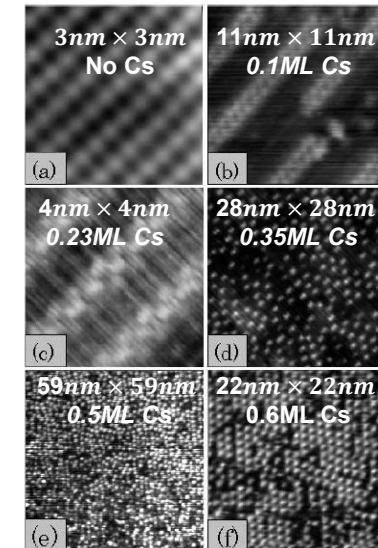
*All GaAs based photocathodes operated at photon energies near the band gap must be activated to **Negative Electron Affinity (NEA)** condition using Cs and O (or other methods) to form a strong surface dipole lowering the electron affinity below the conduction band minimum*



A.J. Van Bommel and J.E. Crombeen, *Surf. Sci.*, **57**, 109 (1976)



S. Karkare et al., *Phys. Rev. B* **91**, 035408 (2015)



Less than 1 monolayer to achieve NEA

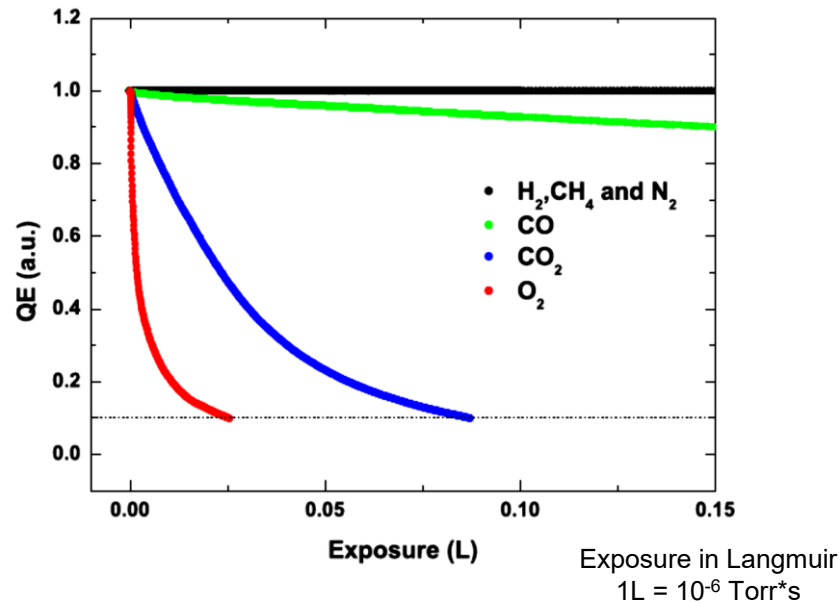
Extremely vacuum sensitive => vacuum better than 10^{-11} Torr are required
Vacuum requirements have so far limited operation in HV DC gun

GaAs QE degradation mechanisms

- Photocathode QE degradation can be induced by the following mechanisms:

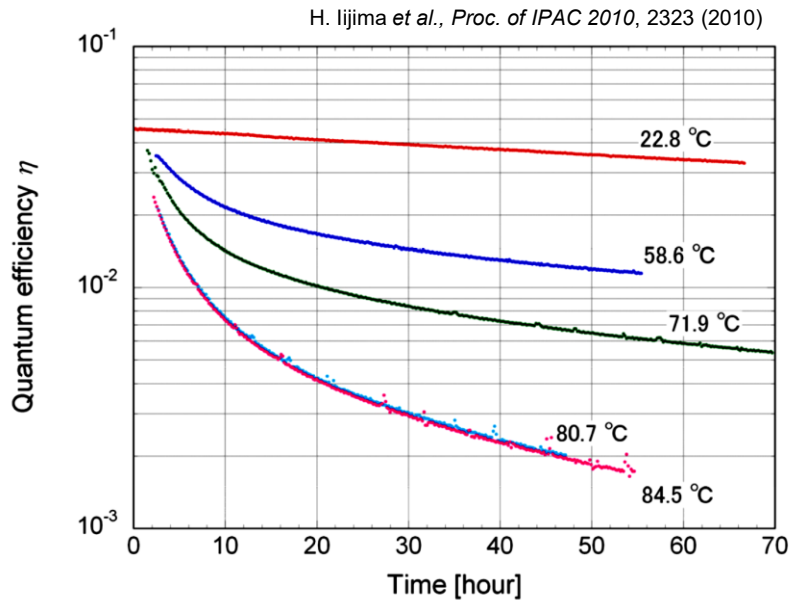
Chemical poisoning

Oxygen is a killer



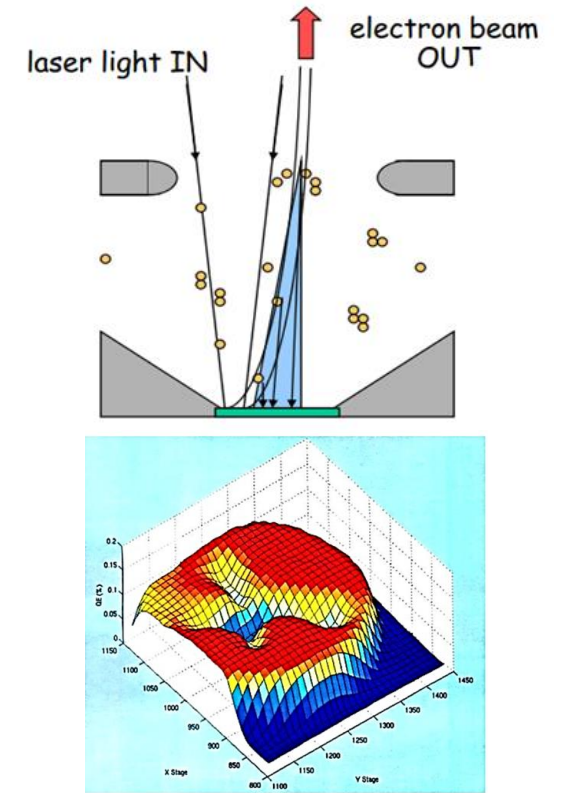
N. Chanlek et al., *J. Phys. D: Appl. Phys.* **47**, 055110 (2014)

Alkali desorption



Relevant for high average power or tightly focused lasers beams

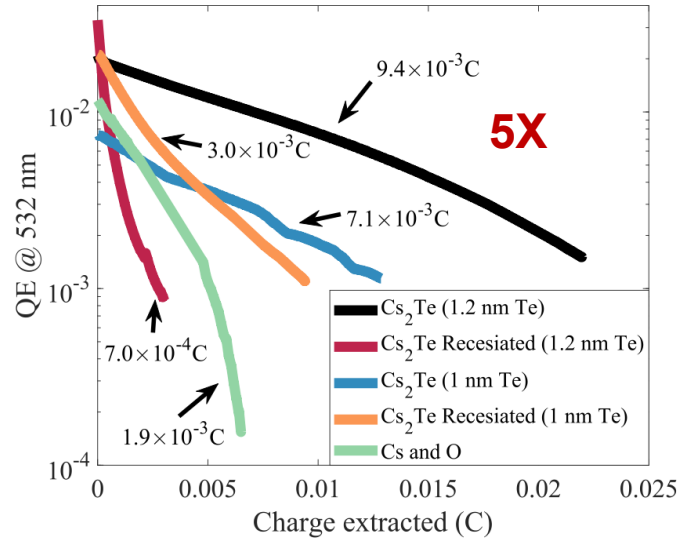
Ion back bombardment



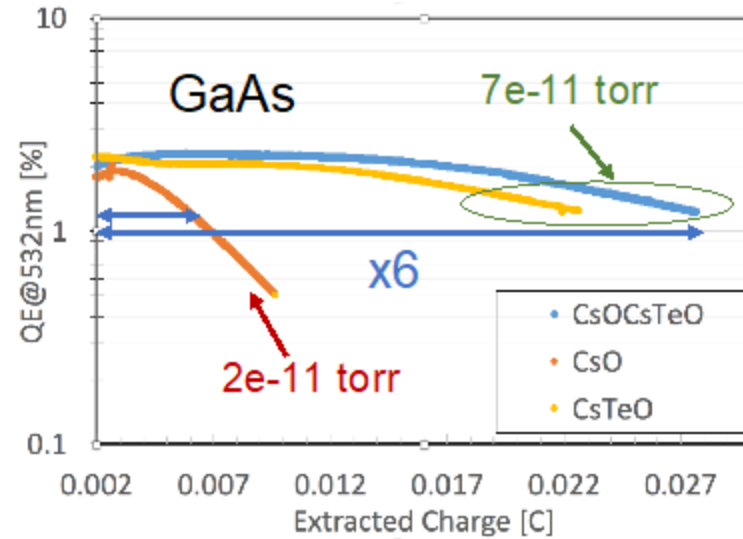
J. Grames et al., *AIP Conf. Proc.* **980**, 110 (2008)

Robust activation layer yield longer lifetimes

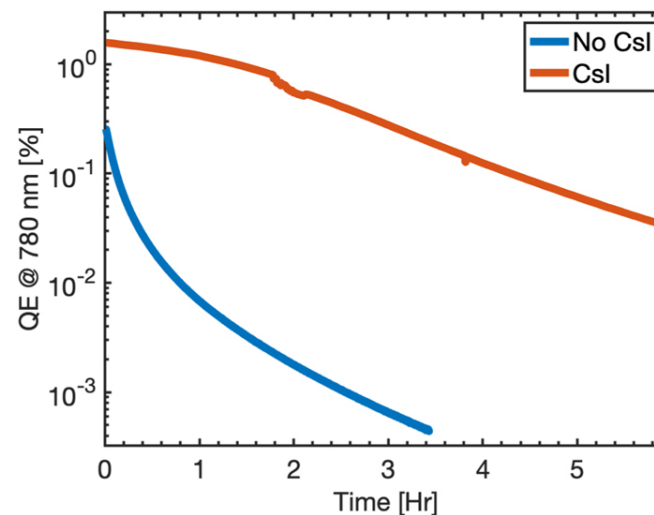
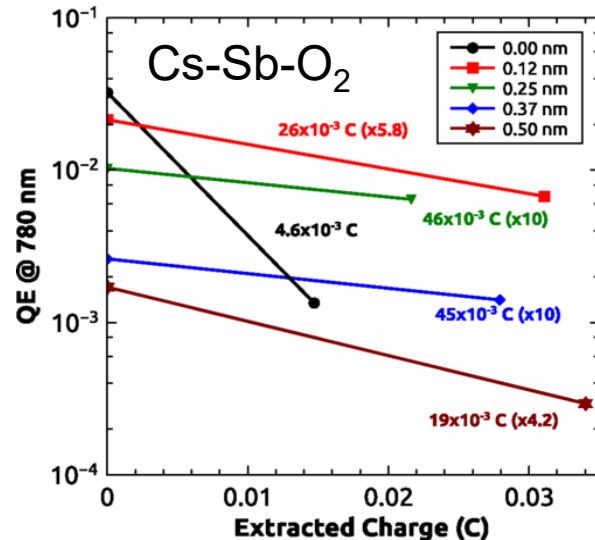
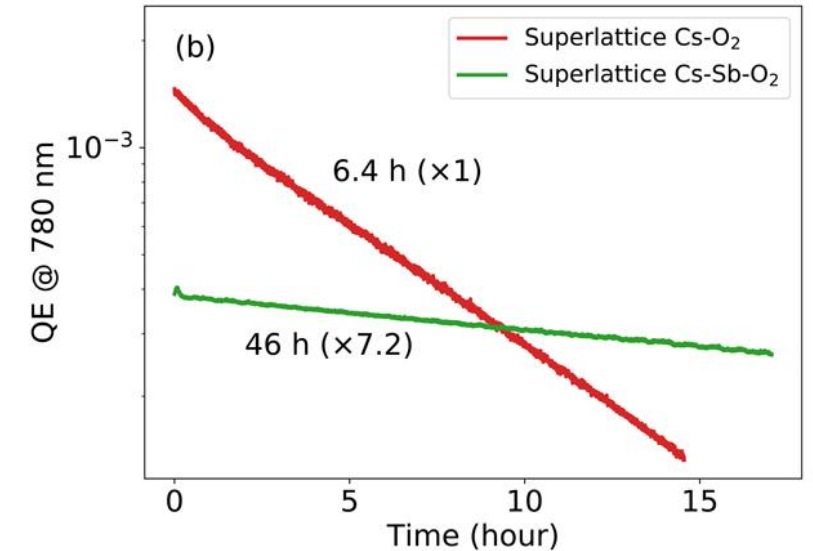
J. Bae et al., Appl. Phys. Lett. **112** (2018) 154101



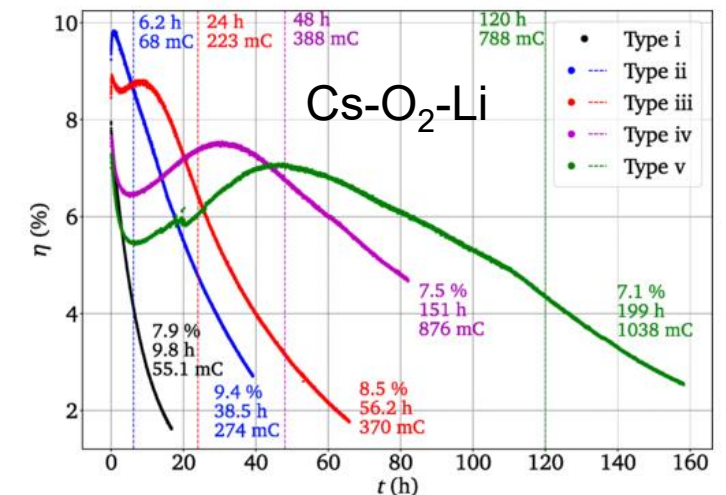
O. Rahman et al., IPAC 2019, TUPTS102



J Bae et al., J. Appl. Phys. **127**, 124901 (2020)



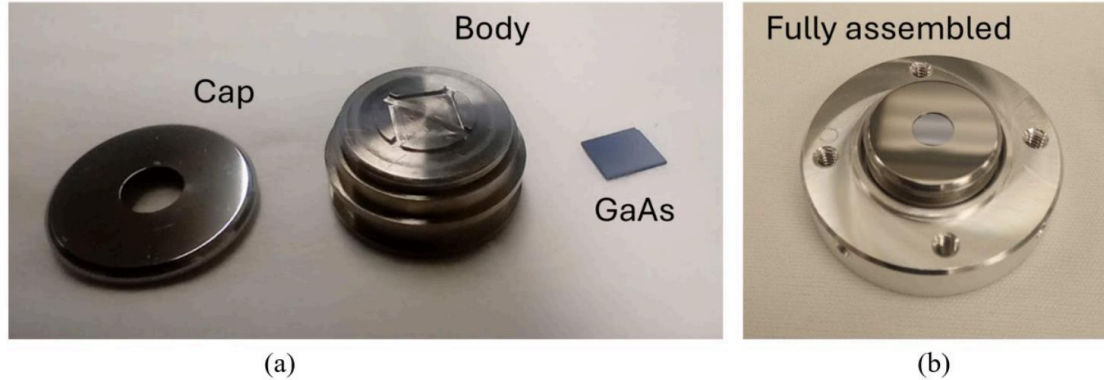
S.J. Levenson et al., J. Appl. Phys. **137**, 224901 (2025)



M. Herbert et al., Phys. Rev. Accel. Beams **28**, 013401 (2025)

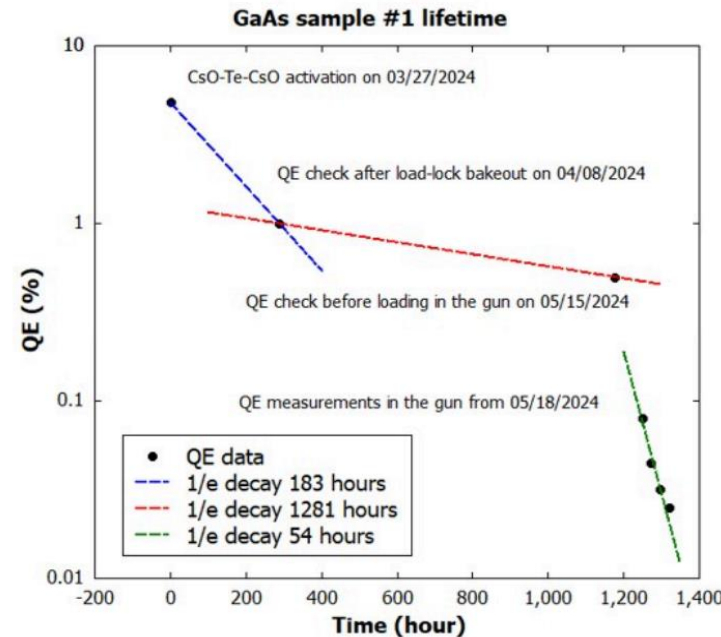
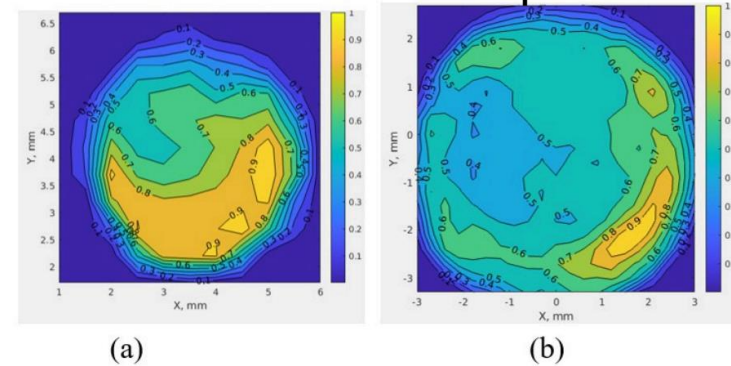
L. Cultrera et al., Phys. Rev. Accel. Beams **23**, 023401 (2020)

CsO-Te-CsO activated photocathode in SRF gun

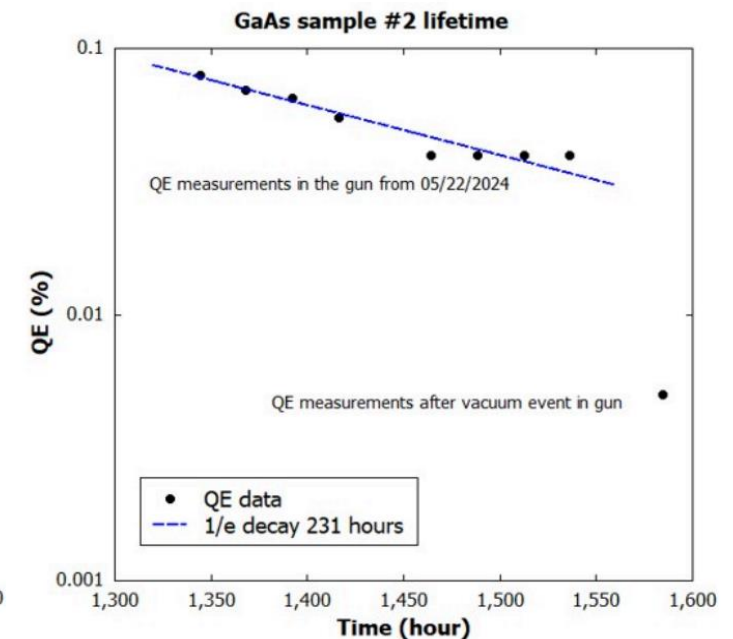


- Cathode holder specially designed for SRF 112 MHz electron gun;
- Cathodes were transferred using a vacuum suitcase from production system to RHIC tunnel;
- Operation was only performed at 532 nm;
- **Cathodes survived transfers and were operated for hundreds of hours;**
- Max $E_{\text{field}} = 12 \text{ MV/m}$
- Max Charge/bunch = 1.2 nC

Relative QE maps



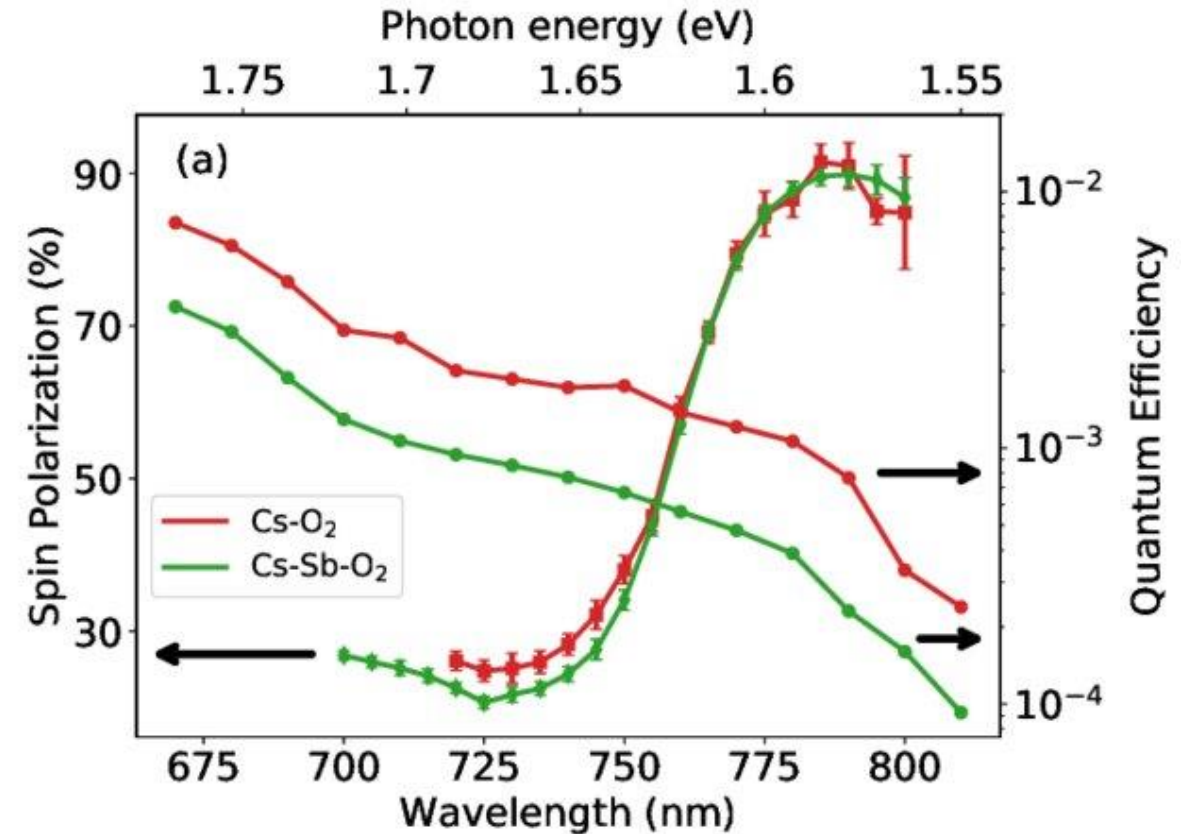
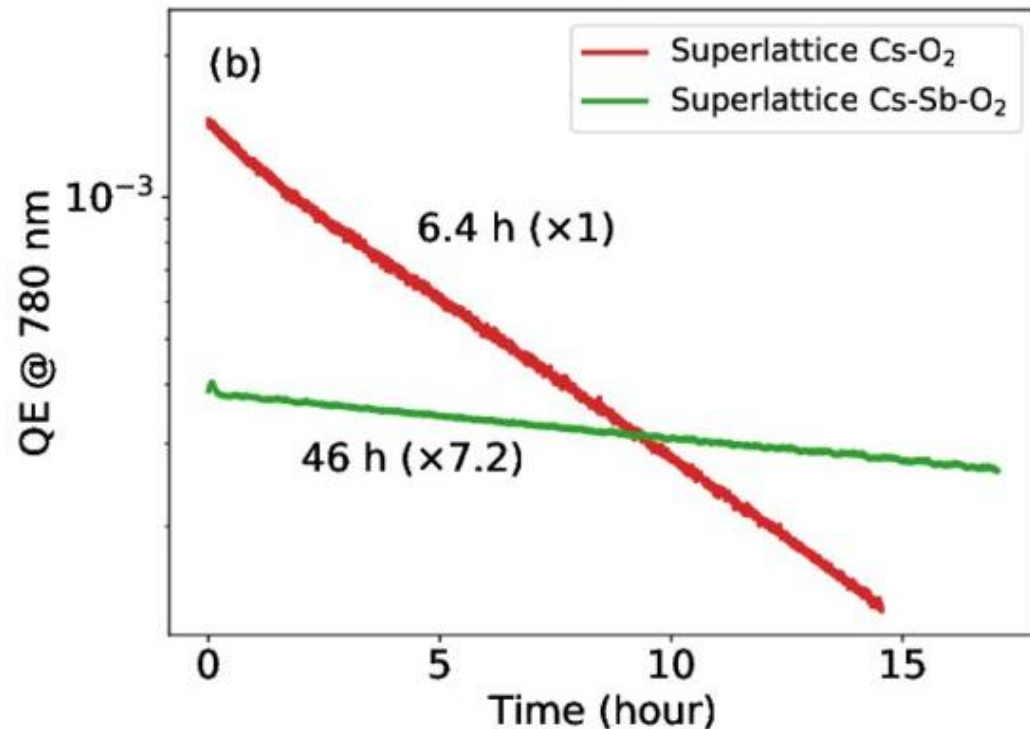
(a)



(b)

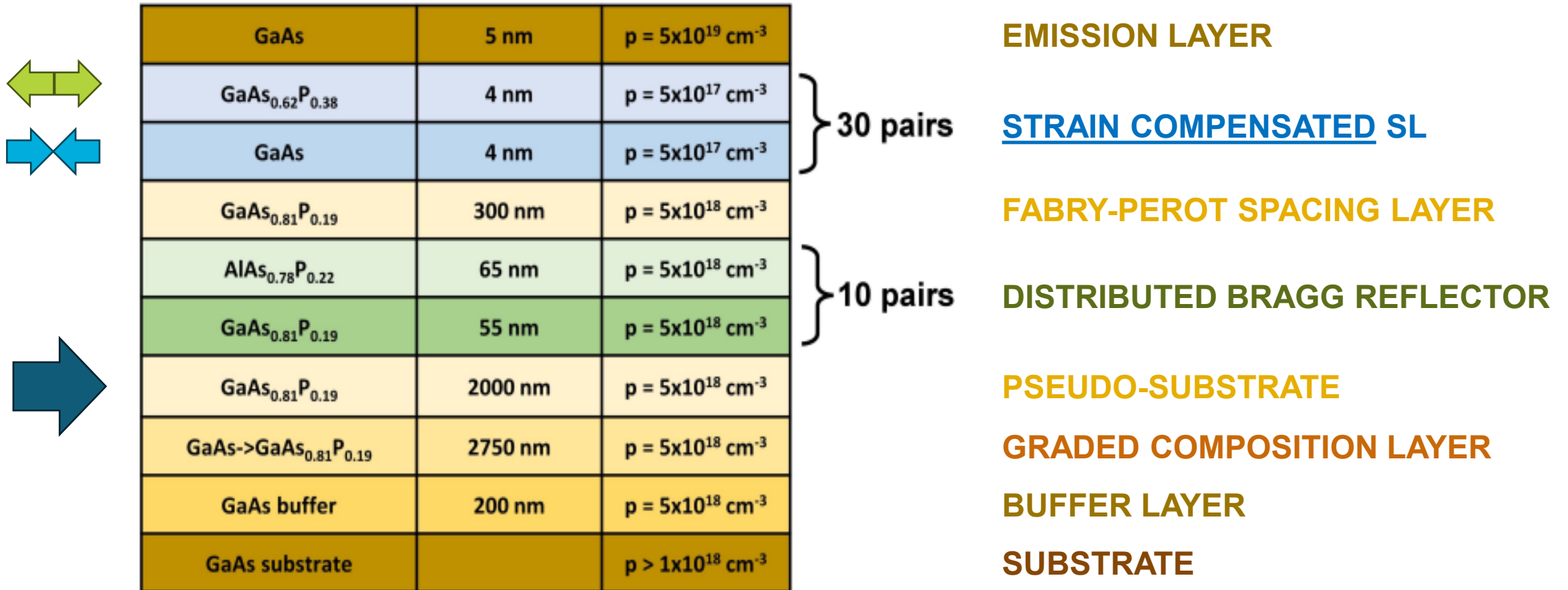
QE and ESP tradeoffs

J Bae et al., J. Appl. Phys. 127, 124901 (2020)



The use of robust activating layers allows to increase lifetime at expenses of QE

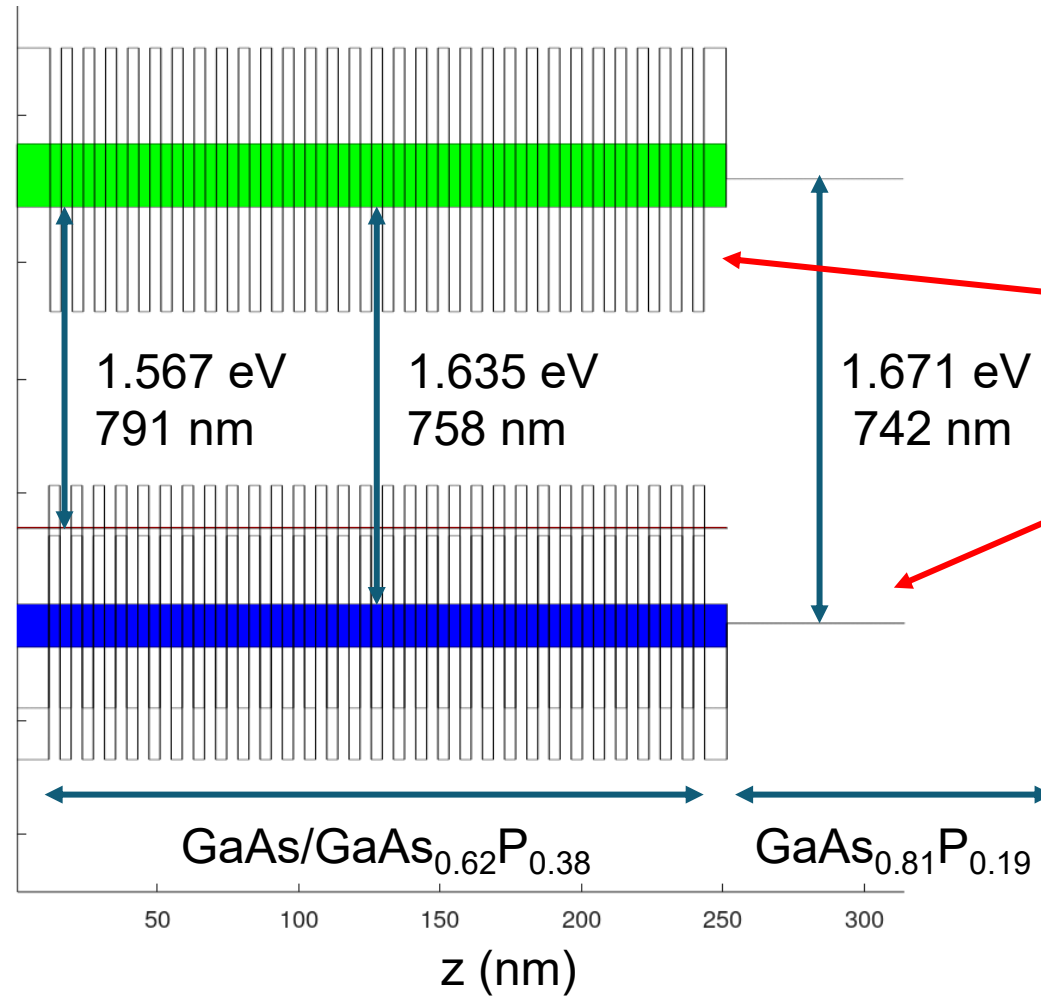
Increasing QE with strain compensated SL-DBR



The diagram illustrates a multi-layer semiconductor structure. On the left, there are three arrows: a green double-headed arrow, a blue double-headed arrow, and a large blue arrow pointing right. The structure is composed of several layers, each with specific material, thickness, and carrier concentration. The layers are grouped into three main sections: a top section with 30 pairs of layers, a middle section with 10 pairs of layers, and a bottom section with a single layer. The layers are color-coded: brown for GaAs, light blue for GaAs_{0.62}P_{0.38}, light blue for GaAs, light orange for GaAs_{0.81}P_{0.19}, light green for AlAs_{0.78}P_{0.22}, green for GaAs_{0.81}P_{0.19}, light orange for GaAs_{0.81}P_{0.19}, light orange for GaAs->GaAs_{0.81}P_{0.19}, light orange for GaAs buffer, and brown for GaAs substrate.

GaAs	5 nm	$p = 5 \times 10^{19} \text{ cm}^{-3}$	} 30 pairs	EMISSION LAYER
GaAs _{0.62} P _{0.38}	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$		<u>STRAIN COMPENSATED SL</u>
GaAs	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$		
GaAs _{0.81} P _{0.19}	300 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$	} 10 pairs	FABRY-PEROT SPACING LAYER
AlAs _{0.78} P _{0.22}	65 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$		DISTRIBUTED BRAGG REFLECTOR
GaAs _{0.81} P _{0.19}	55 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$		
GaAs _{0.81} P _{0.19}	2000 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$		PSEUDO-SUBSTRATE
GaAs->GaAs _{0.81} P _{0.19}	2750 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$		GRADED COMPOSITION LAYER
GaAs buffer	200 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$		BUFFER LAYER
GaAs substrate		$p > 1 \times 10^{18} \text{ cm}^{-3}$		SUBSTRATE

Miniband calculation

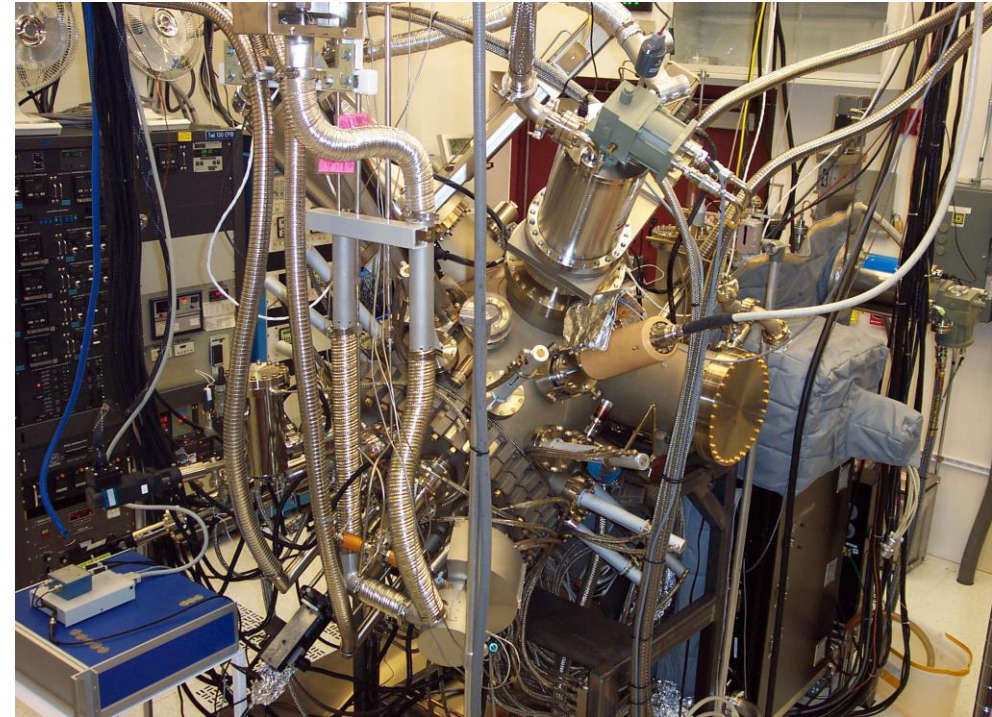
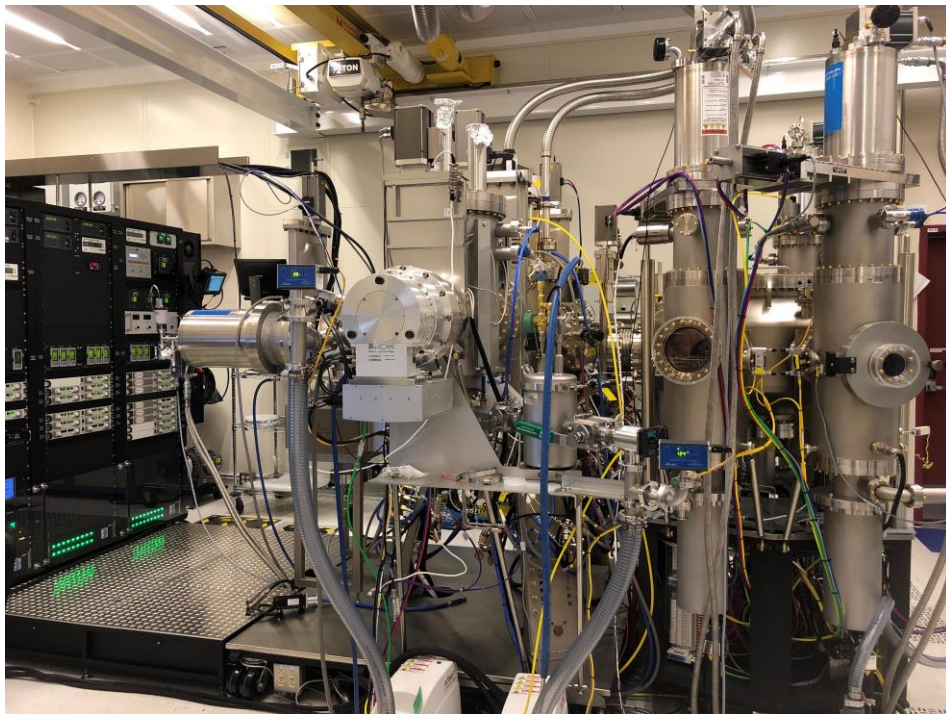


In plan strain estimated at $\pm 0.7\%$
 HH-LH separation is estimated at 66 meV

GaAs	5 nm	$p = 5 \times 10^{19} \text{ cm}^{-3}$	} 30 pairs
$\text{GaAs}_{0.62}\text{P}_{0.38}$	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$	
GaAs	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$	
$\text{GaAs}_{0.81}\text{P}_{0.19}$	300 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$	} 10 pairs
$\text{AlAs}_{0.78}\text{P}_{0.22}$	65 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$	
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$\text{GaAs} \rightarrow \text{GaAs}_{0.81}\text{P}_{0.19}$	2750 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$	
GaAs buffer	200 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$	
GaAs substrate		$p > 1 \times 10^{18} \text{ cm}^{-3}$	

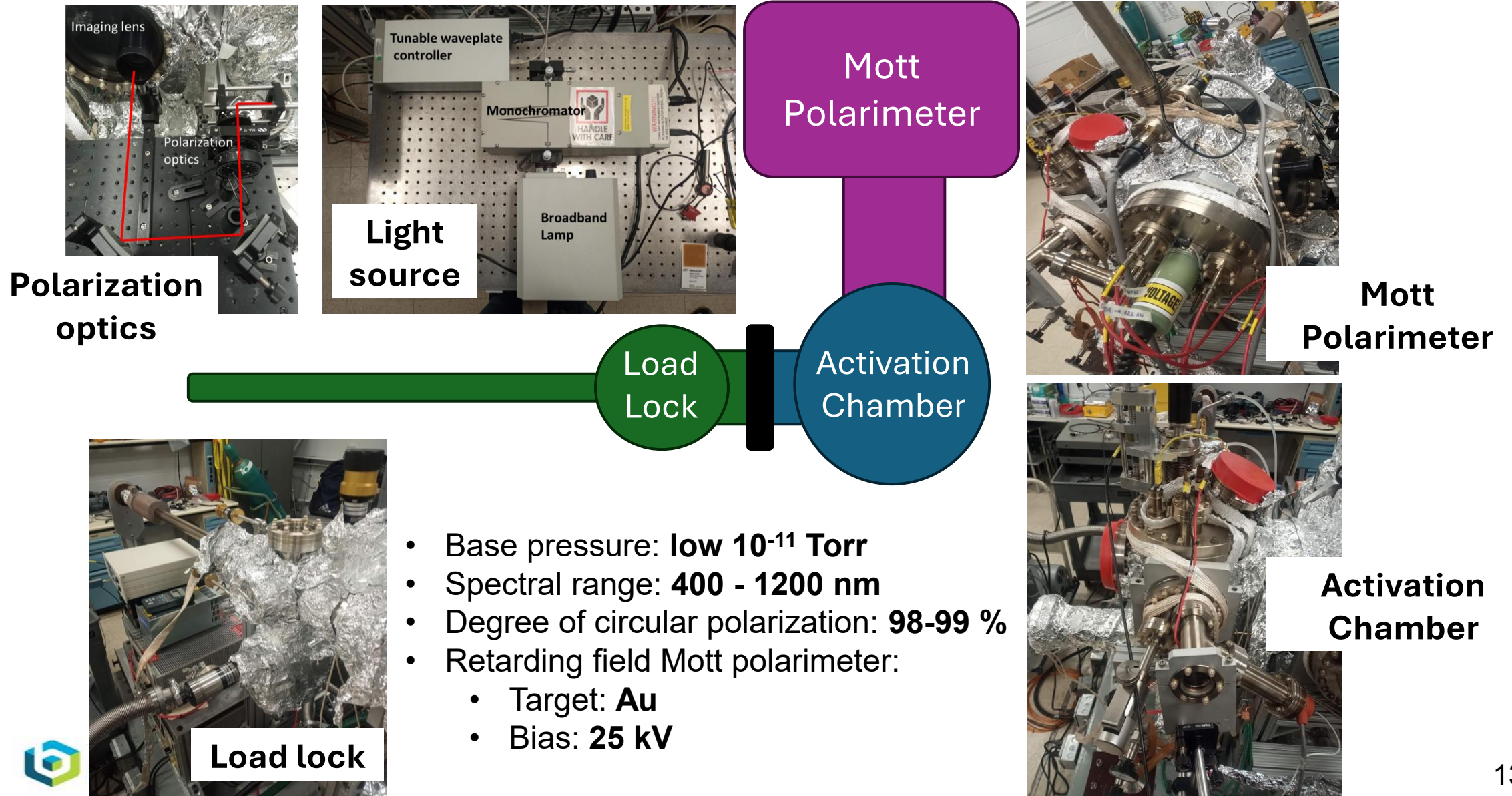
Molecular Beam Epitaxy

Sandia National Laboratories has state of the art MBE infrastructure, and the expertise required to perform the growth of III-V layered structures

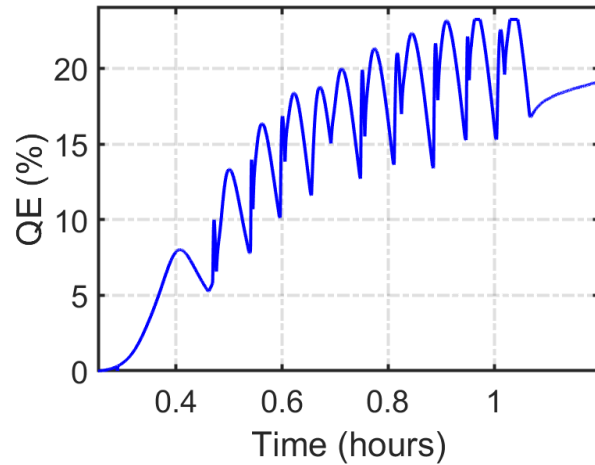


- Highly stable flux control:
 - As is supplied from high purity solid sources
 - P is supplied by phosphine thermal crackers
- Dual-zone substrate heater provides better temperature uniformity over the 3" wafer
- P-Type doping is achieved with carbon obtained using a CBr₄ gas injector
- Wafers were capped with arsenic to protect the surface from oxidation.

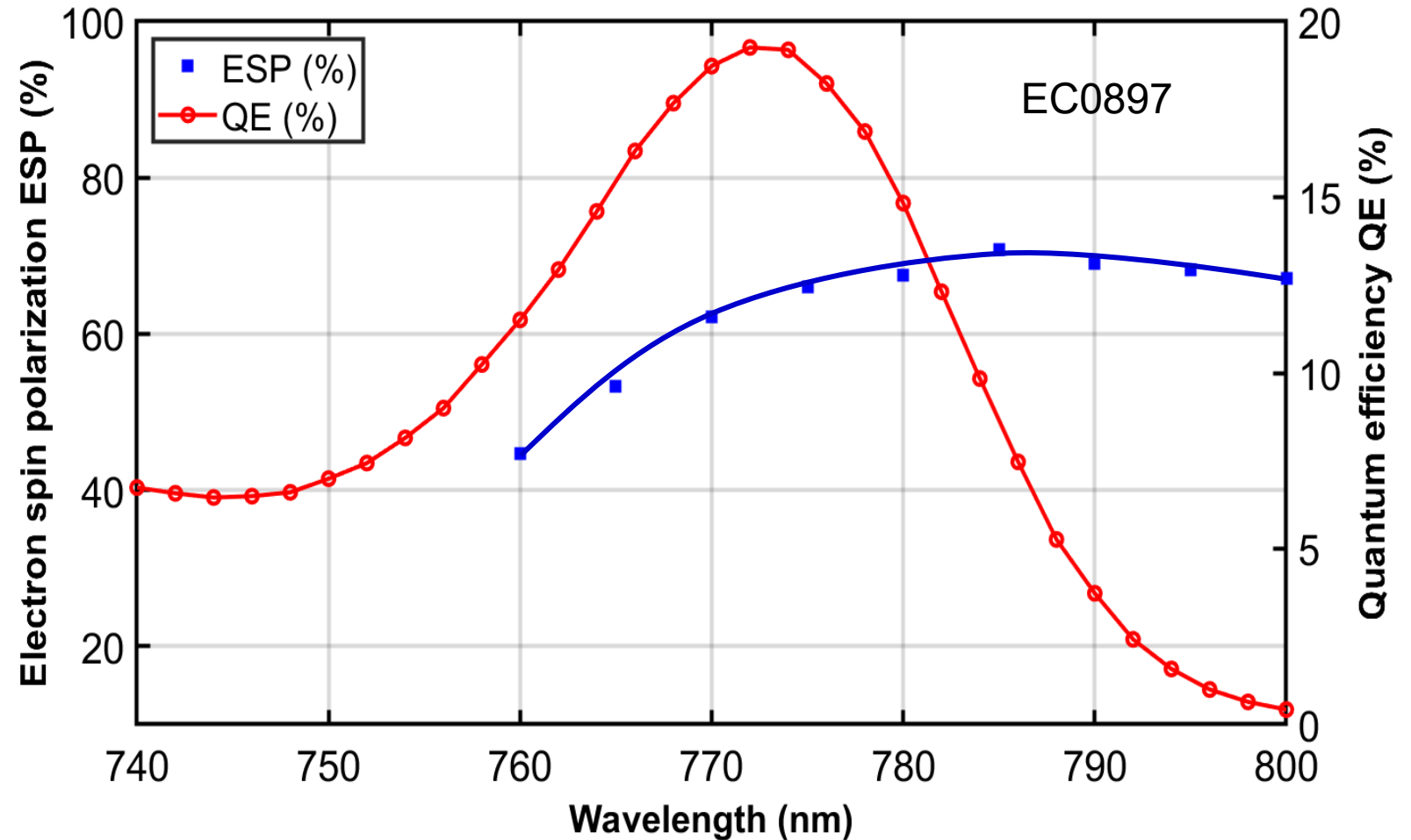
Experimental setup at BNL



QE and ESP – initial design

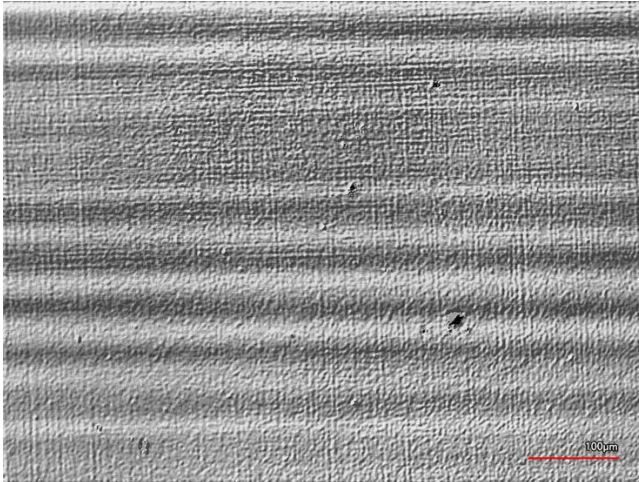


- Photon wavelength – **532 nm**
- Alternate exposure to Cs and O₂ until peak QE saturates
- Maximum QE at the end of activation ~ 20%
- In-plane strain ~0.7%
- HH-LH estimated at about 70 meV

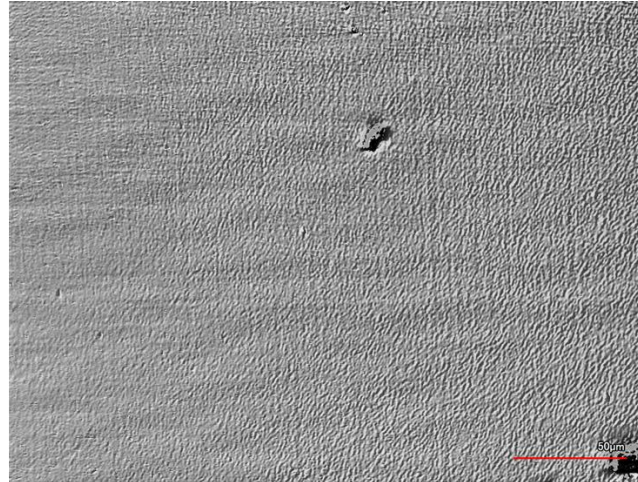


ESP = ~70%, QE = 15% at 780 nm

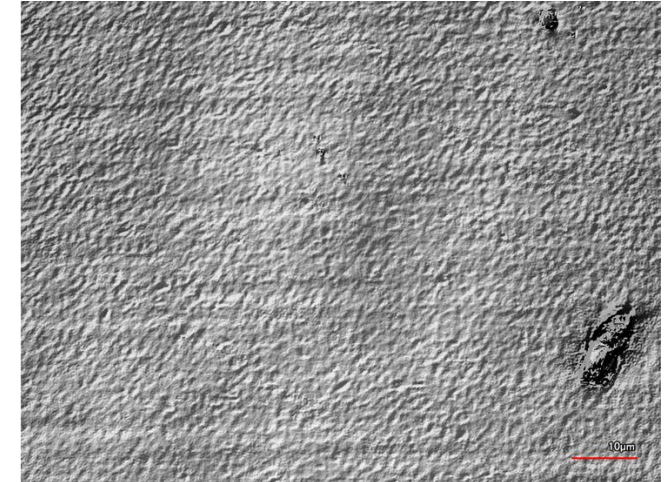
ECO-897 Surface Morphology



20X



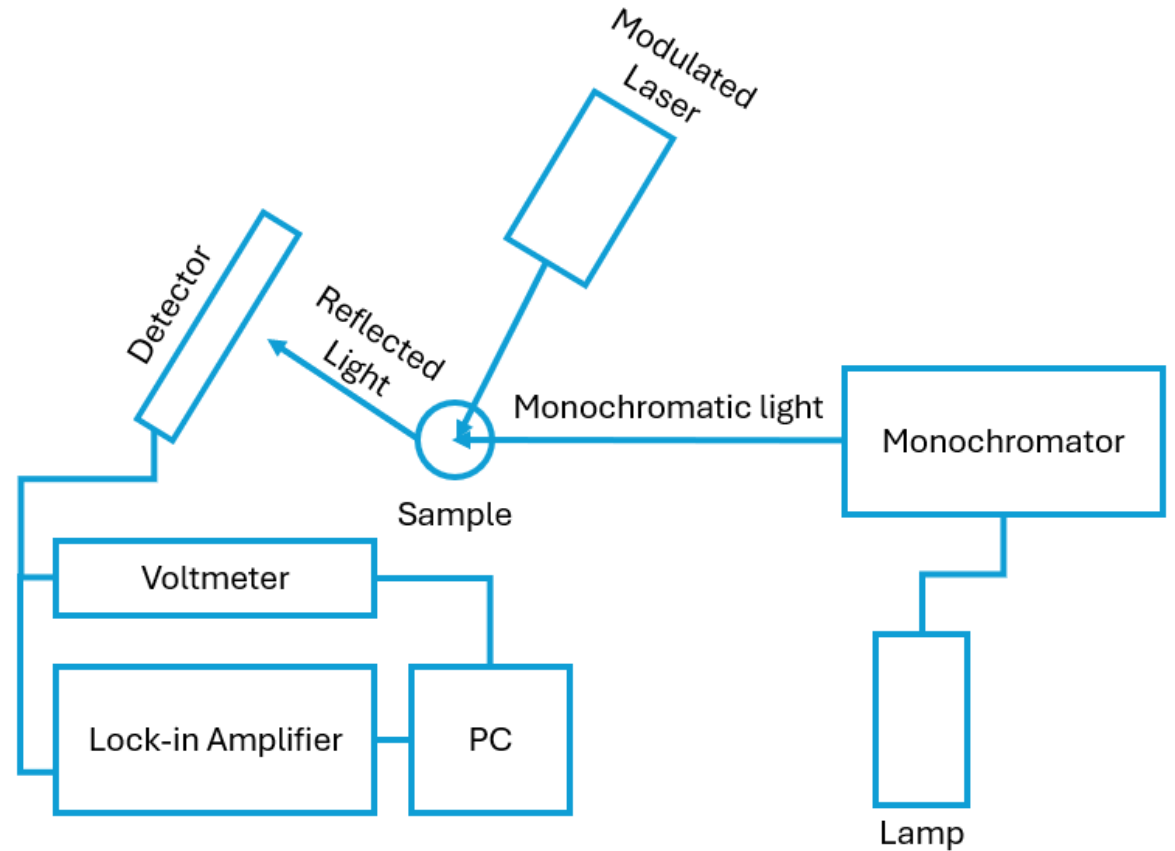
50X



150X

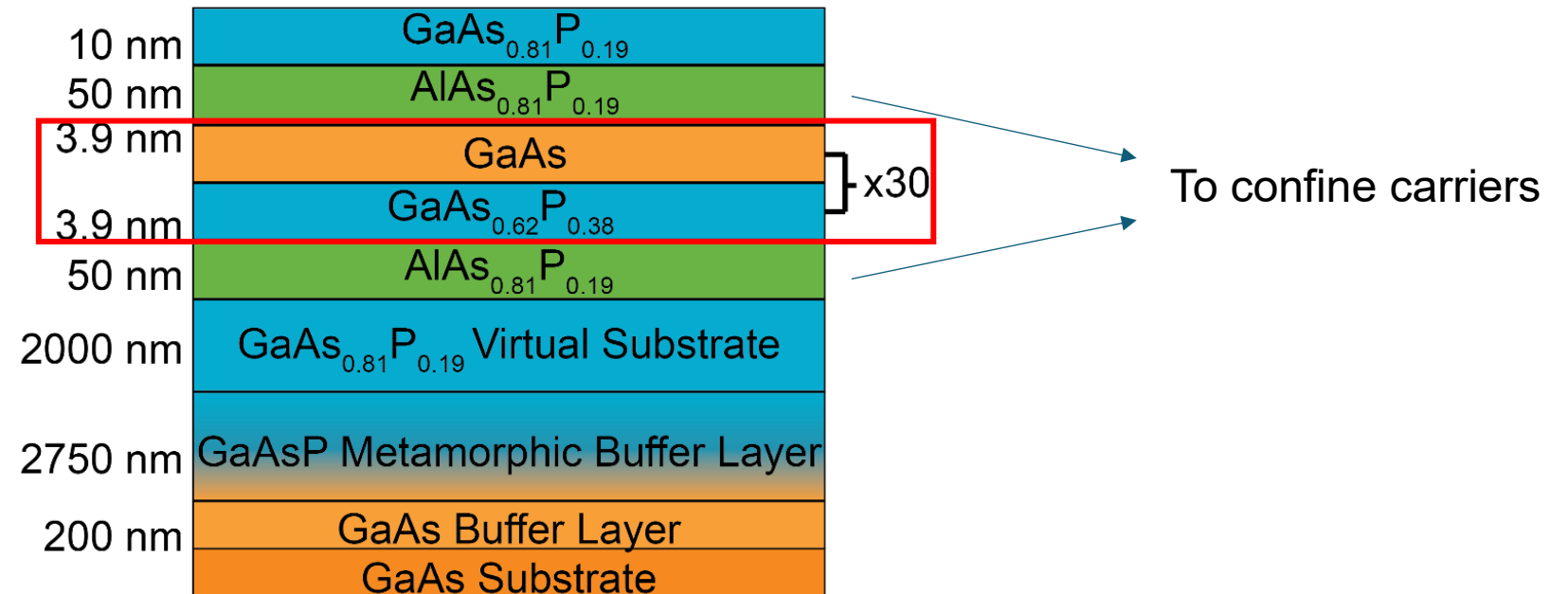
Photorefectance

- Consists of a probe (white) light and a pump (green laser)
- Pump beam modulates the electric field in the sample
- Measure the change in reflectivity of the sample and normalize by dividing out the reflectance

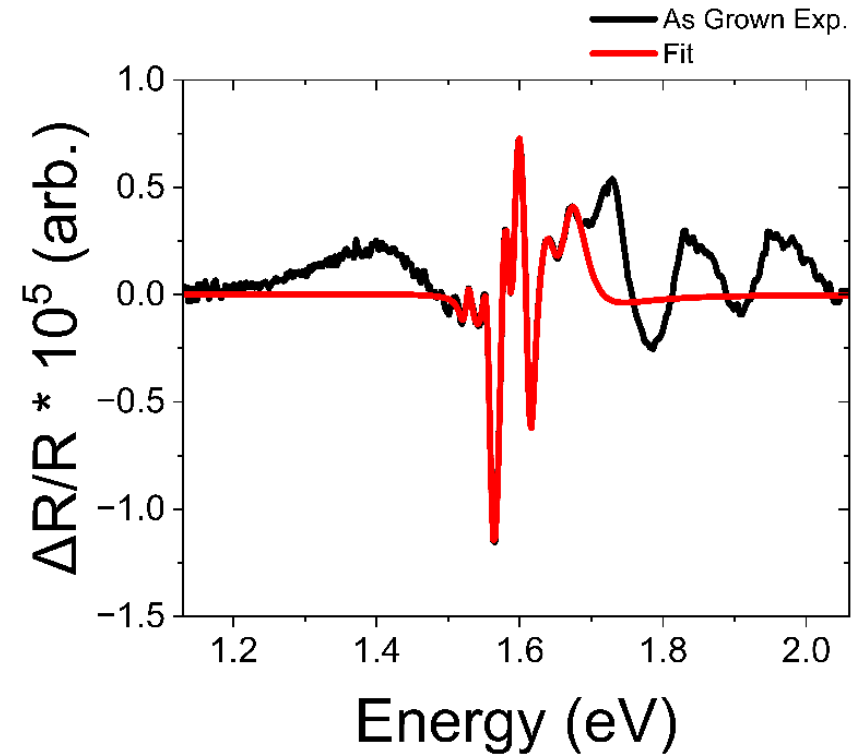
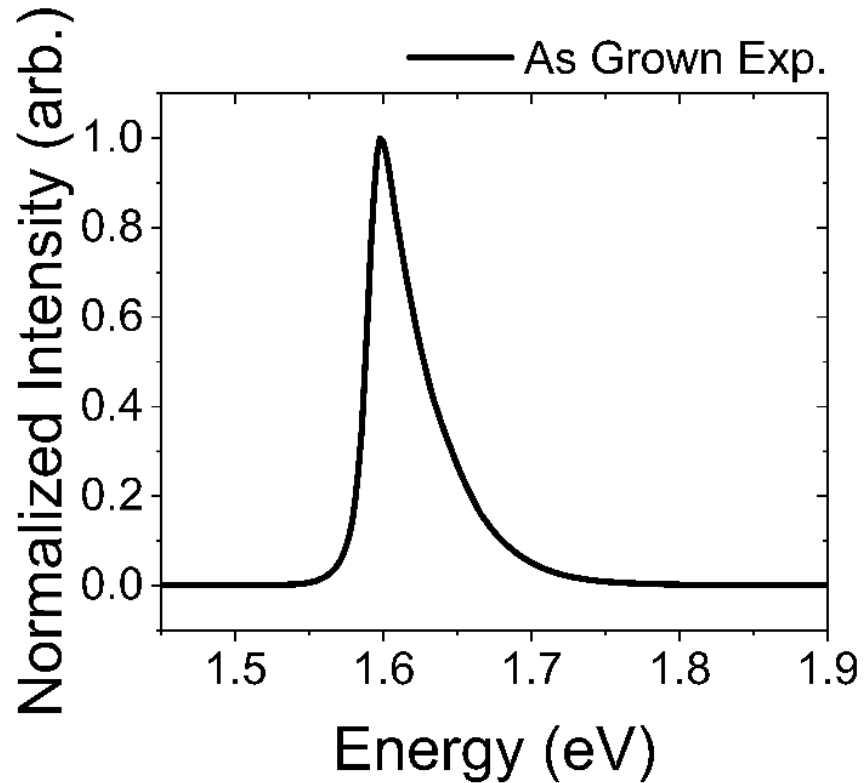


Structure

Nominally the same structure from the record QE photocathode, without the DBR



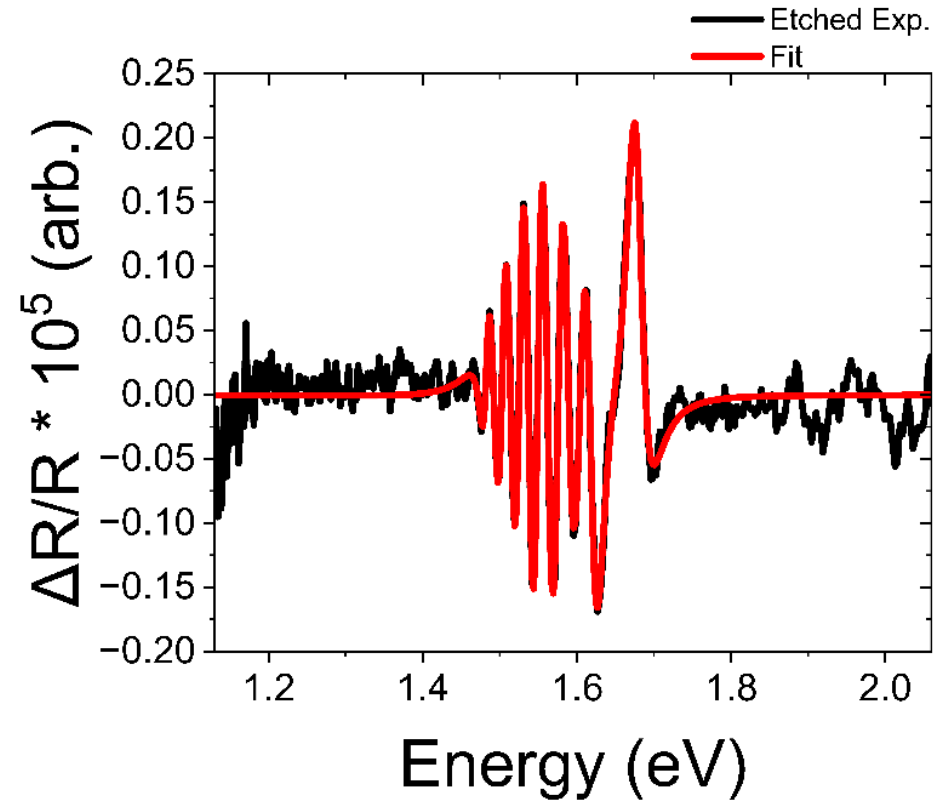
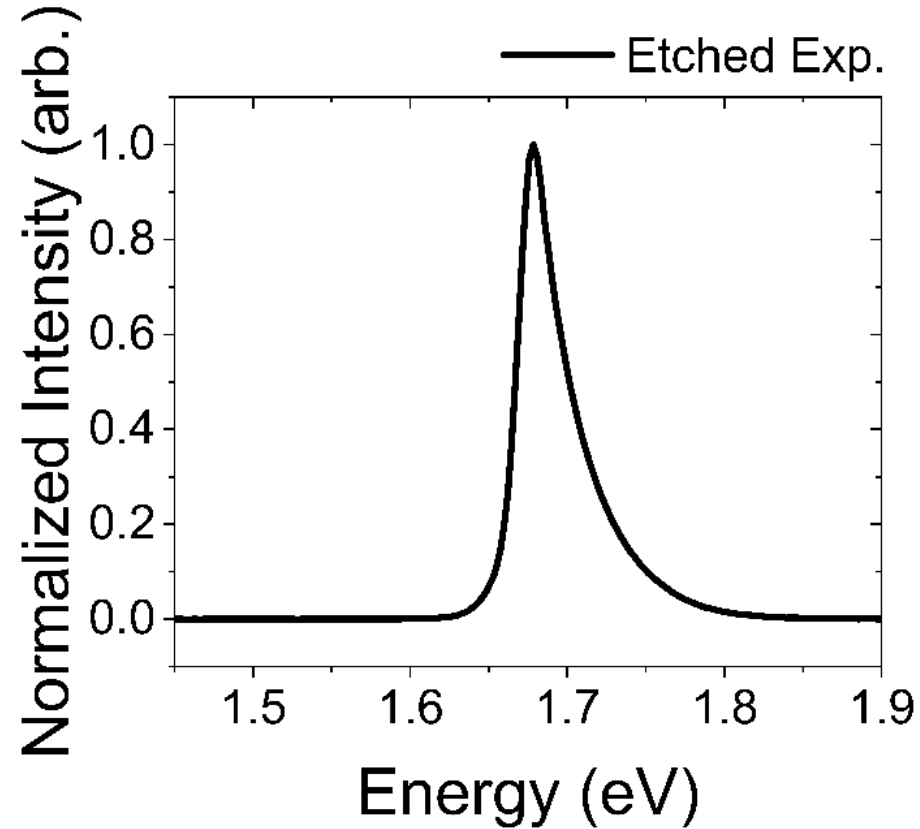
As-Grown Sample



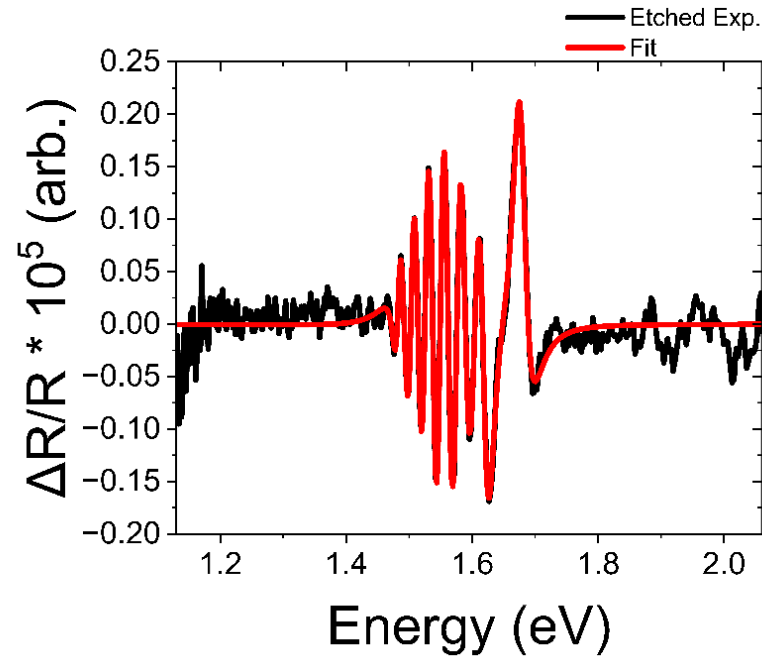
Courtesy of A. Muhowski, M. McDonough

Etched Sample

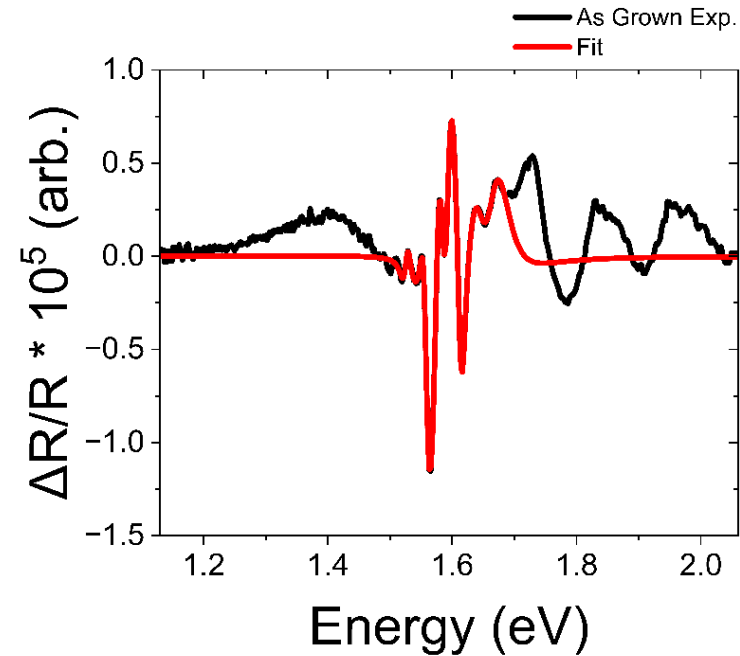
Sample was etched down about 300 nm into the virtual substrate to remove the superlattice structure



Comparison of Fitting Results



E_{cp} (eV)	Identity
1.483	Metamorphic Buffer Layer
1.503	Metamorphic Buffer Layer
1.524	Metamorphic Buffer Layer
1.547	Metamorphic Buffer Layer
1.564	Metamorphic Buffer Layer
1.582	Metamorphic Buffer Layer
1.616	Metamorphic Buffer Layer
1.679	E_g of Virtual Substrate



E_{cp} (eV)	Identity
1.527	Metamorphic Buffer Layer
1.557	Metamorphic Buffer Layer
1.579	CB/HH
1.614	Metamorphic Buffer Layer
1.636	CB/LH
1.662	E_g of Virtual Substrate

HH/LH Splitting of 57 meV

Modification to the FP spacing layer

GaAs	5 nm	$p = 5 \times 10^{19} \text{ cm}^{-3}$
$\text{GaAs}_{0.62}\text{P}_{0.38}$	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$
GaAs	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$
$\text{GaAs}_{0.81}\text{P}_{0.19}$	300 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
$\text{AlAs}_{0.78}\text{P}_{0.22}$	65 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
$\text{GaAs}_{0.81}\text{P}_{0.19}$	55 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
$\text{GaAs}_{0.81}\text{P}_{0.19}$	2000 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
$\text{GaAs} \rightarrow \text{GaAs}_{0.81}\text{P}_{0.19}$	2750 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
GaAs buffer	200 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
GaAs substrate		$p > 1 \times 10^{18} \text{ cm}^{-3}$

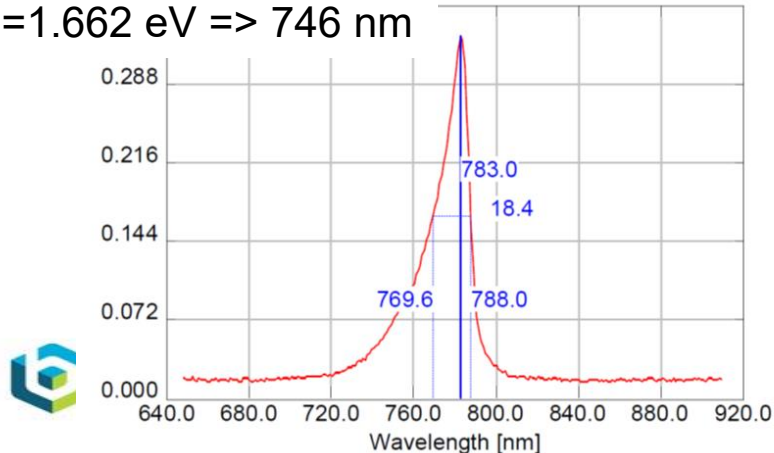
Changed the composition
of the Fabry Perot
spacing layer



The increased band
gap increases the
energy required for
electrons excitation in
this layer

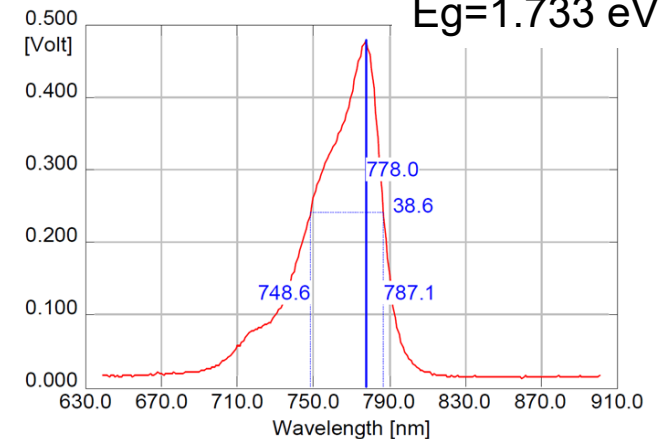
GaAs	5 nm	$p = 5 \times 10^{19} \text{ cm}^{-3}$
$\text{GaAs}_{0.62}\text{P}_{0.38}$	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$
GaAs	4 nm	$p = 5 \times 10^{17} \text{ cm}^{-3}$
$\text{Al}_{0.15}\text{Ga}_{0.85}\text{As}_{0.81}\text{P}_{0.19}$	300 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
$\text{AlAs}_{0.78}\text{P}_{0.22}$	65 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
$\text{GaAs}_{0.81}\text{P}_{0.19}$	55 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
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GaAs buffer	200 nm	$p = 5 \times 10^{18} \text{ cm}^{-3}$
GaAs substrate		$p > 1 \times 10^{18} \text{ cm}^{-3}$

$E_g = 1.662 \text{ eV} \Rightarrow 746 \text{ nm}$

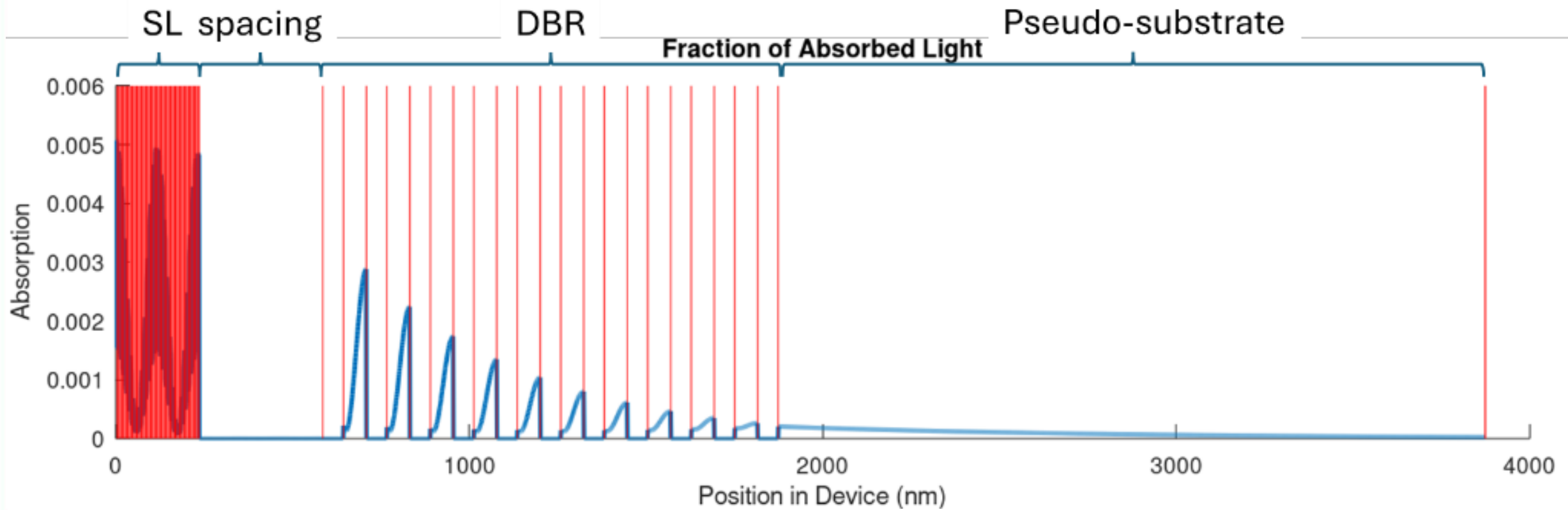


Photoluminescence
measurements shows
expected longer tail at
shorter wavelengths

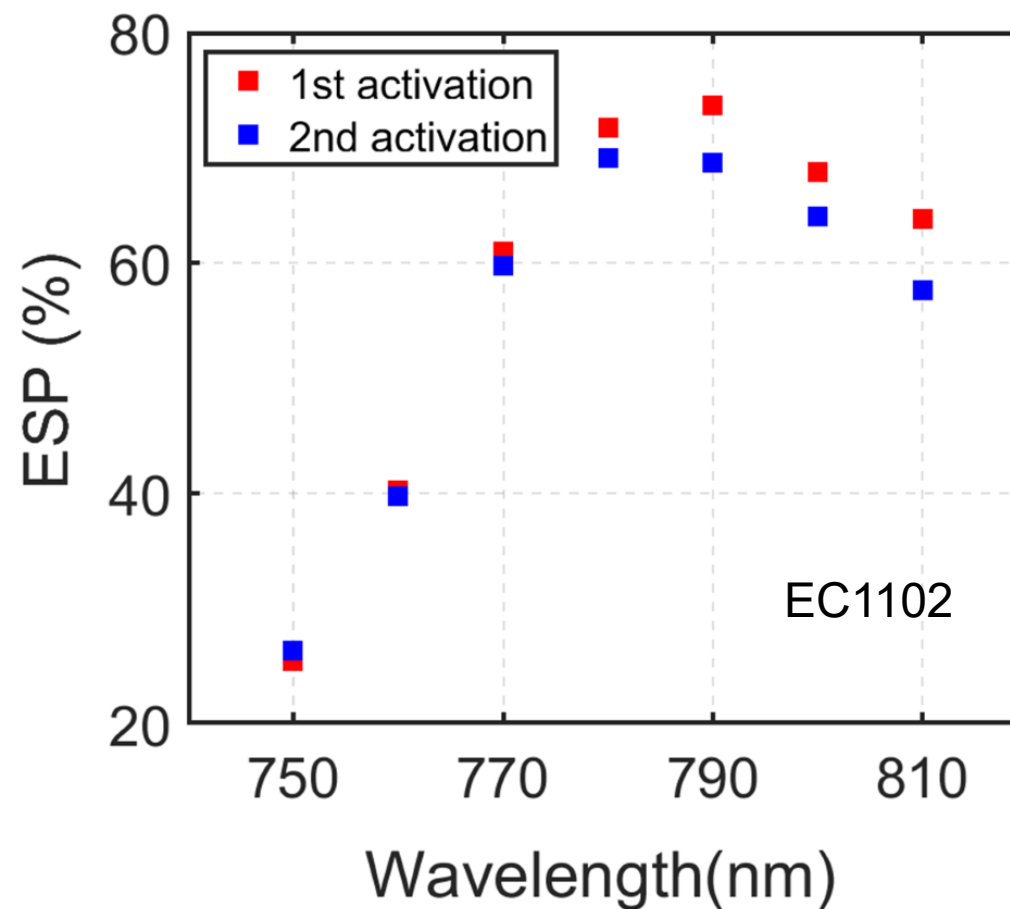
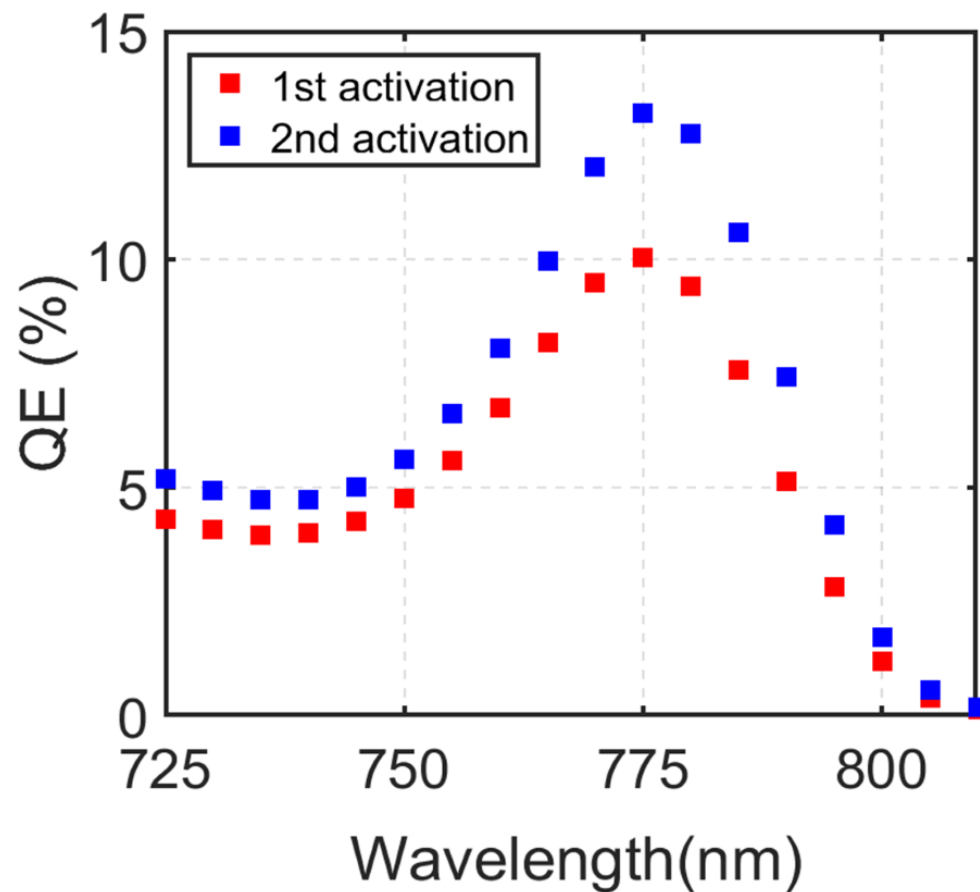
$E_g = 1.733 \text{ eV} \Rightarrow 715 \text{ nm}$



Optical absorption within the structure



QE and ESP from 2nd iteration



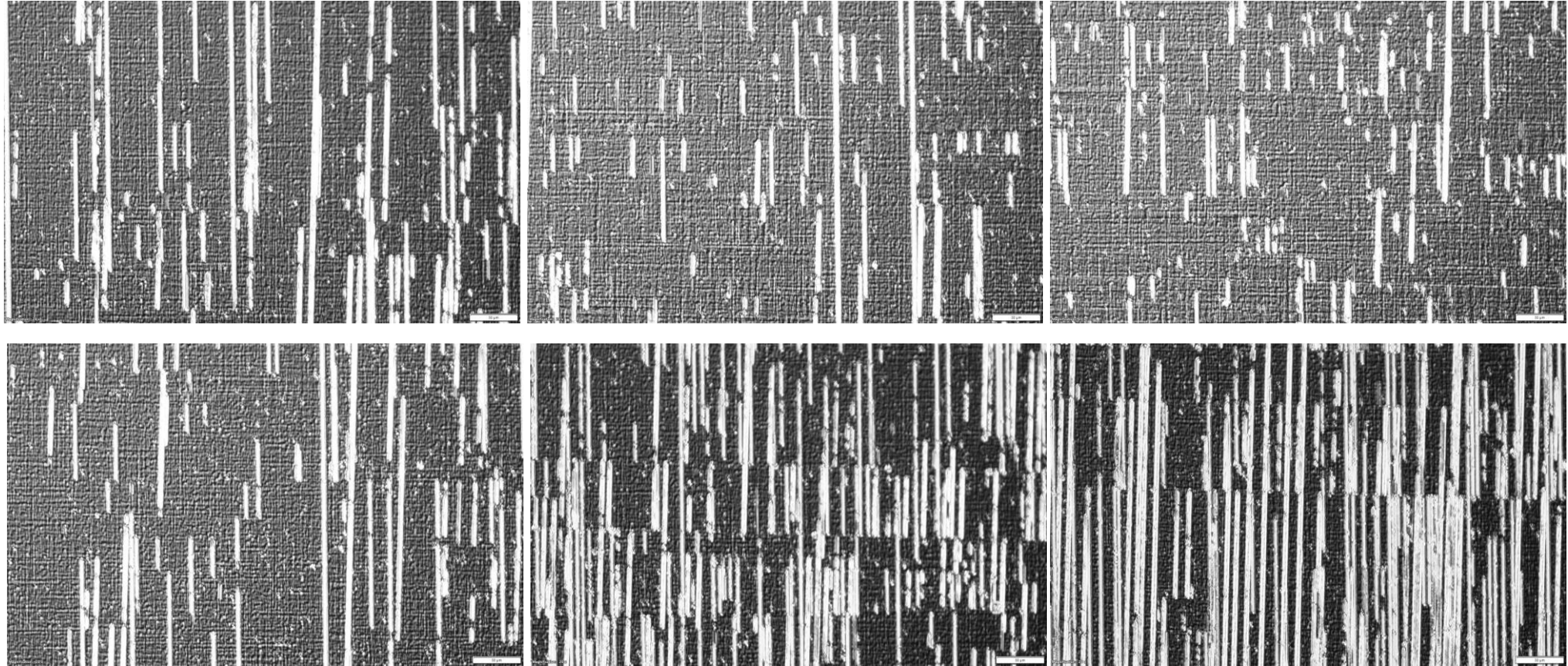
We still observe very high QEs but not the expected improvement in the ESP

Morphology of the samples

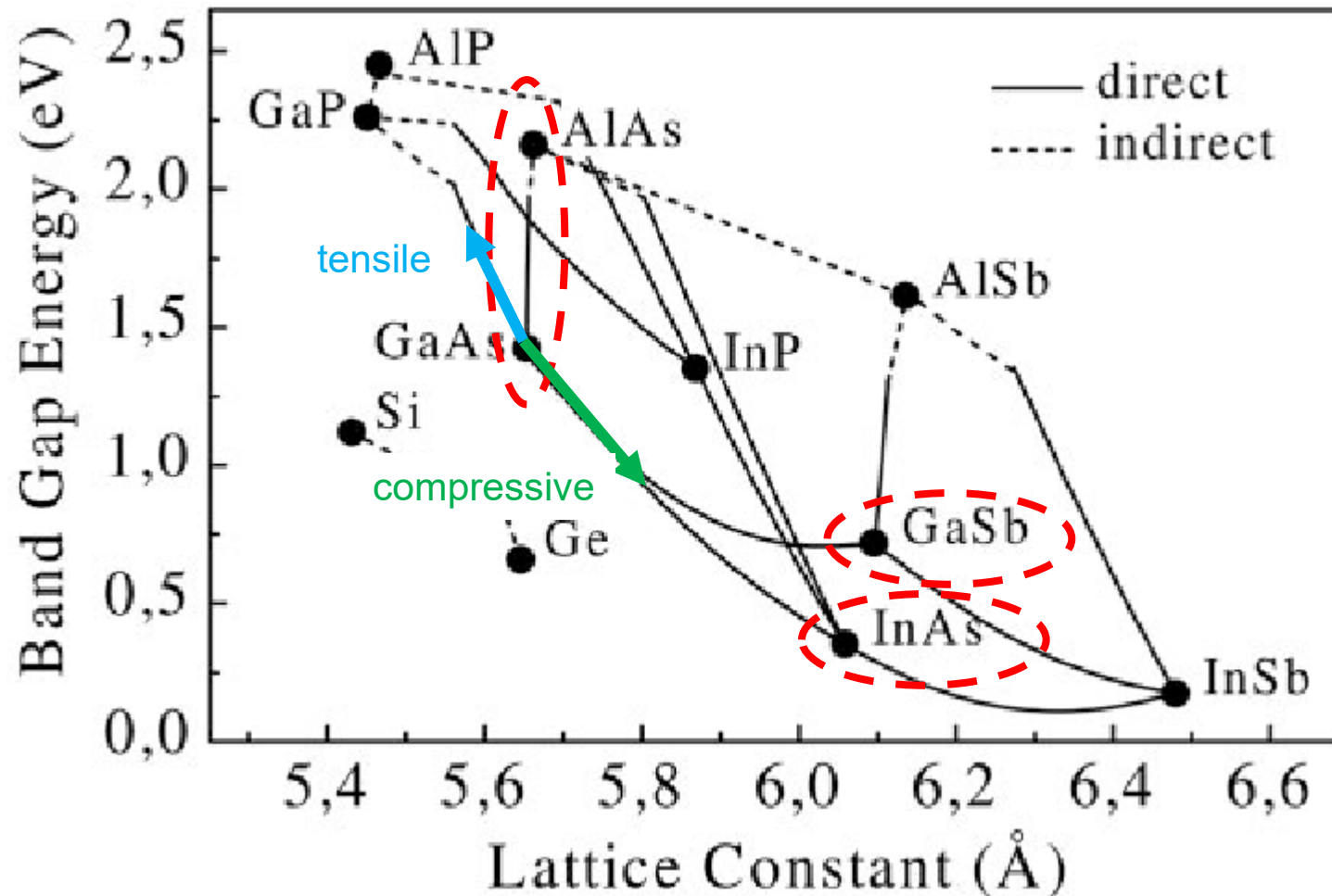
High density of slip-planes possibly from thread dislocations

Originated on the underlying DBR layers?

TBC from Transmission Electron Microscopy measurement



Can we use GaAs pristine surface to grow upon it?



Grow directly on GaAs

- No need to grow the pseudo-substrate
- Less material to be grown
- Higher substrate quality

DBR made out with GaAs/AlAs

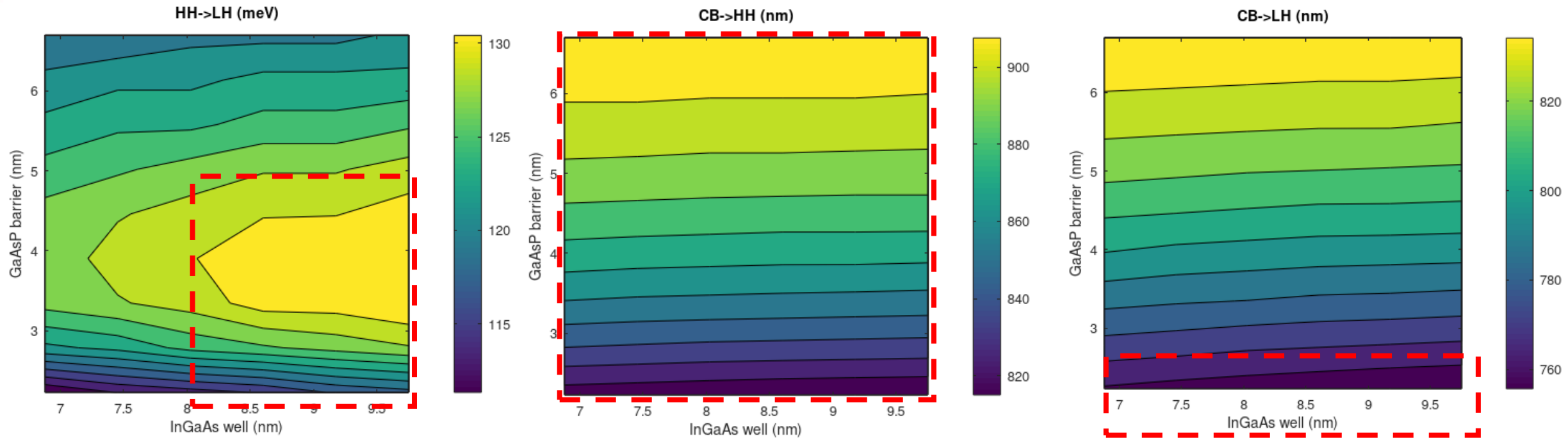
- Binary compounds

Two option for the SL layers

- GaAsP/InGaAs
- GaAsP/GaAsSb

SL based on $\text{GaAs}_{0.62}\text{P}_{0.38}/\text{In}_{0.20}\text{Ga}_{0.80}\text{As}$

Parametric studies varying the width of barrier and wells in strain compensated SL



HH-LH separation is large
=> high ESP

(about 2x w.r.t. our SL-DBR
which has ~70 meV)

CB-HH => Absorption edge

Larger than 800 nm is good as it
ensure large QE @800nm

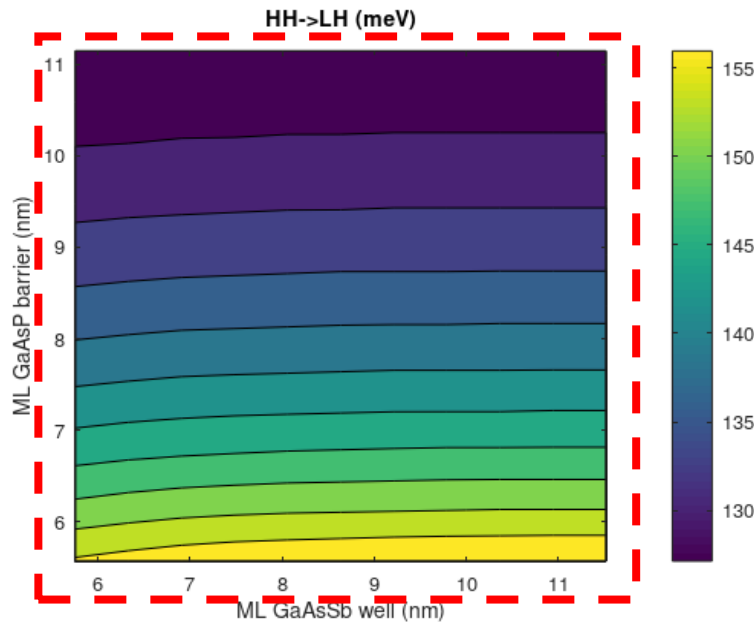
CB-LH => onset of ESP
depolarization

We wanted to have this to be
shorter than 800 nm

SL based on $\text{GaAs}_{0.60}\text{P}_{0.40}/\text{GaAs}_{0.75}\text{Sb}_{0.25}$

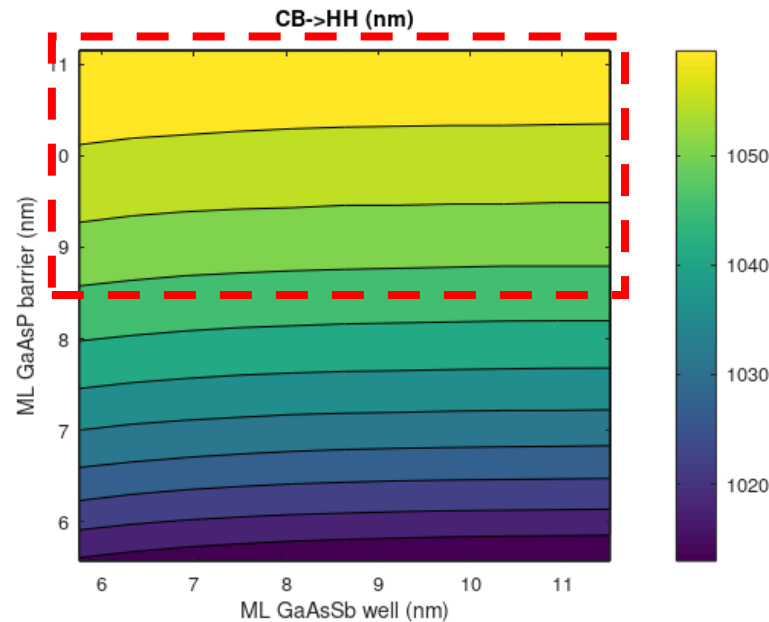
Parametric studies varying the width of barriers and wells in strain compensated SL

Designed to be conveniently operated with fiber lasers at 1030nm



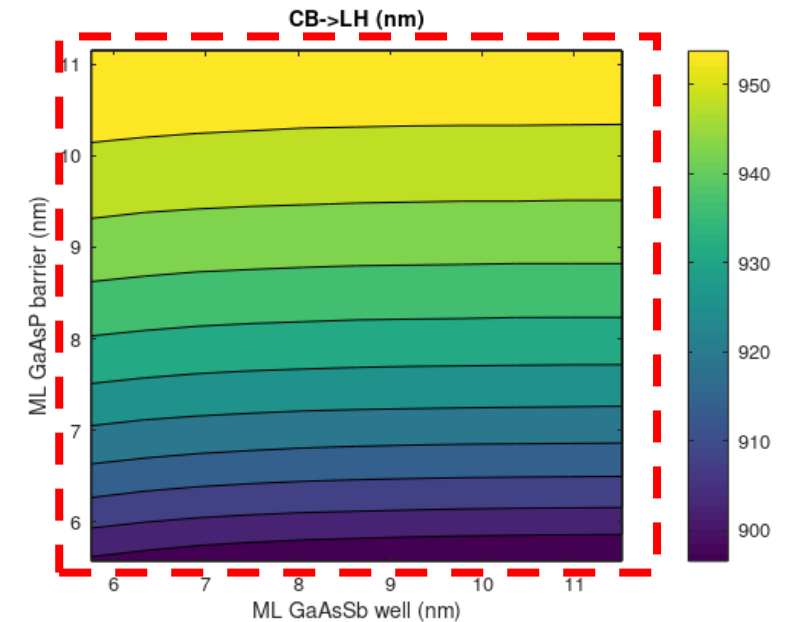
HH-LH (>130 meV)
⇒ high ESP

-2x the currently used SL-



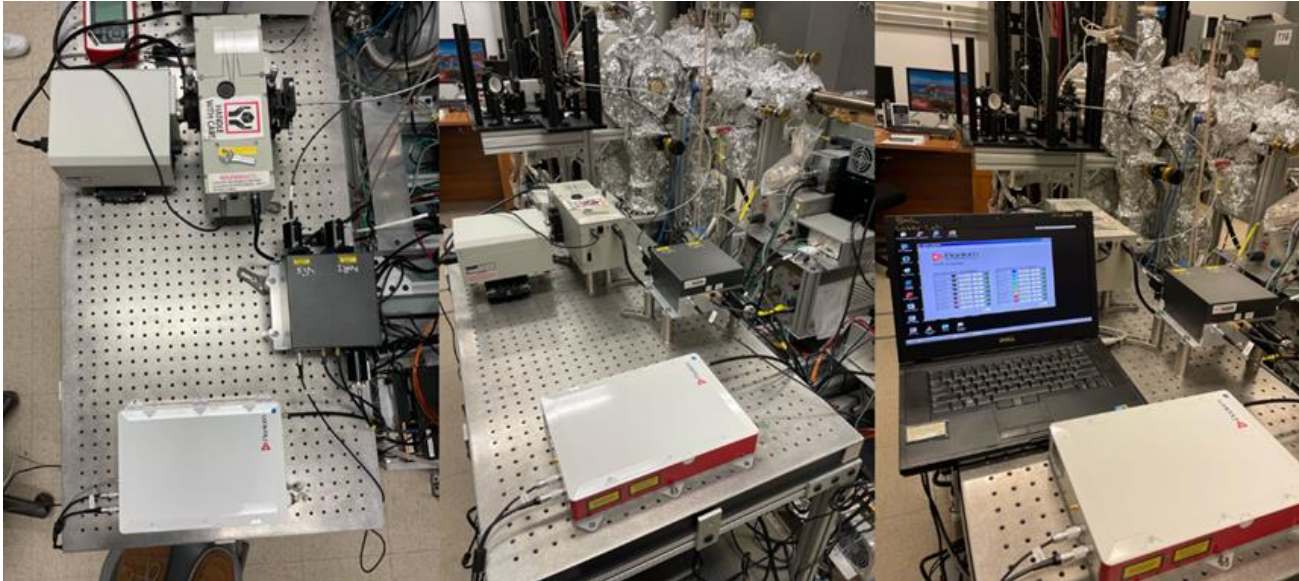
SL band edge is larger than 1030 nm

Ensure large optical absorption for
Yb fiber laser operation

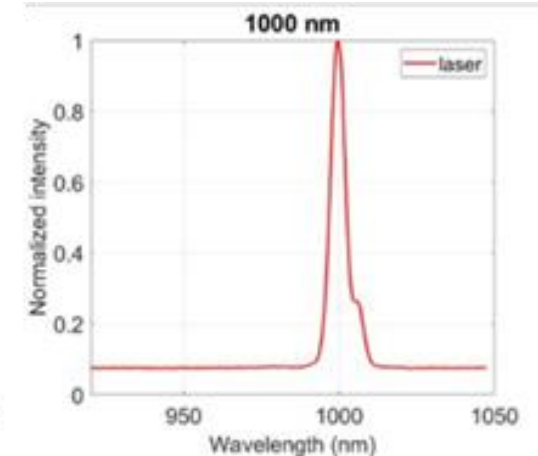
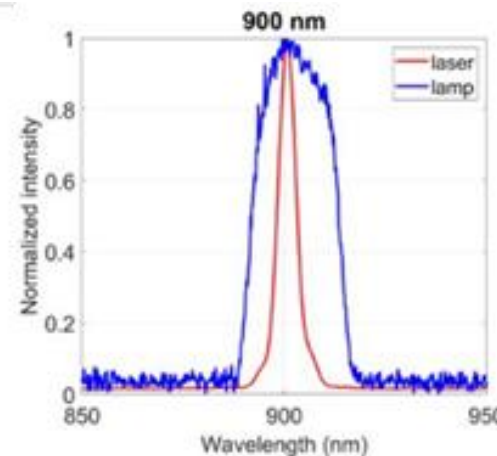
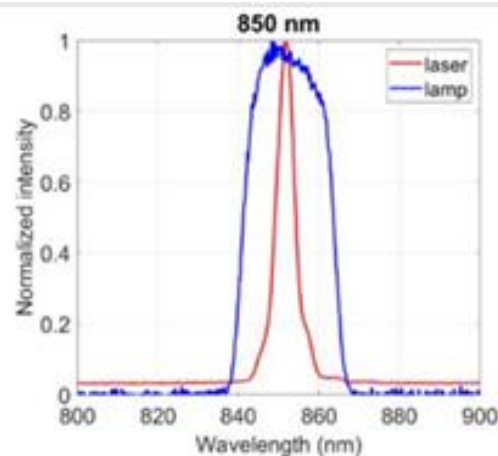
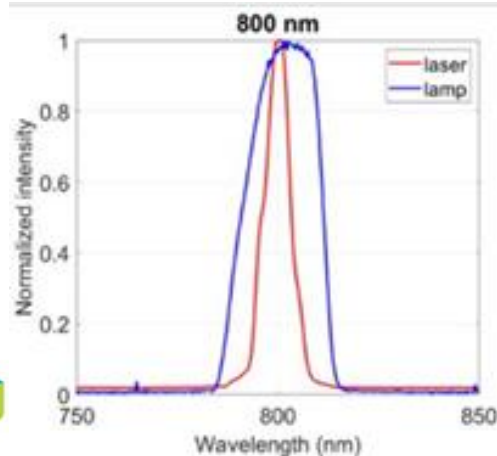


Wavelength for the onset of ESP
depolarization is shifted towards
wavelengths much shorter than
1030 nm

Optical system upgrade



- The intensity vs. bandwidth of our lamp system is not optimal.
- The tungsten lamp does not provide enough photons at wavelength larger than 900 nm.
- We installed and re-commissioned a supercontinuum laser which provides more photons and a narrower bandwidth for next measurement



Conclusions

- Several robust activating layers yielded longer dark lifetimes
- QE and ESP tradeoffs call for higher QEs to increase operational lifetime
- Achieved record high QE from a SL DBR with high ESP
- Lattice matching on GaAs can simplify growth
 - GaAsP/InGaAs operated at ~800 nm
 - GaAsP/GaAsSb operated at ~1030 nm

Collaboration	Wavelength (nm)	QE (%)	ESP (%)	FoM (QE*ESP ²)
Nagoya/KEK/LBNL	780	1.6	92	1.35
SVT/Jlab	775	6.4	84	4.51
BNL/SNL rev.1	775	18.8	66	8.18
BNL/SNL rev.2	780	9	72	4.66

Thank you!

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